

# TID results of a new 0.13um technology for future HEP ASIC design

S. Michelis, F.Faccio, D.Cornale

# Last year news

[http://globalfoundries.com/newsroom/press-releases/2014/10/20/globalfoundries-to-acquire-ibm's-microelectronics-business?utm\\_source=homepage&utm\\_medium=brief&utm\\_campaign=IBM](http://globalfoundries.com/newsroom/press-releases/2014/10/20/globalfoundries-to-acquire-ibm's-microelectronics-business?utm_source=homepage&utm_medium=brief&utm_campaign=IBM)

The screenshot shows the GlobalFoundries website homepage. At the top, there is a navigation bar with links for About, Technology Solutions, Design Solutions, Services, Manufacturing, Newsroom, Careers, Support, and Contact Us. To the right of the navigation bar is a search bar and a 'Search' button. The main content area features a large blue banner with the word 'ANNOUNCEMENT' in white capital letters. Below it, there is a circular icon with a left-pointing arrow and the text 'GLOBALFOUNDRIES TO ACQUIRE IBM'S MICROELECTRONICS BUSINESS'. A 'Read More' button is located at the bottom of this section. To the right of the banner, there is a logo for 'GLOBALFOUNDRIES' next to '&' and the 'IBM' logo, set against a background of a hand holding a computer chip over a blurred circuit board.

The future of our legacy 130nm technology is uncertain, therefore it is necessary to find a suitable alternative technology

A new technology has been found and it needs to be tested for radiation tolerance.

This seminar is focused on Total Ionizing Dose (TID) tests done on the new 130nm technology

# The new 130nm technology has different fabs

Fab 14  
12 inches  
(6 sub/year)

Fab 6  
8 inches  
(2 sub/year)

Fab 12  
12 inches  
(4 sub/year)

Fab: semiconductor fabrication plant

# The new 130nm technology has different fabs

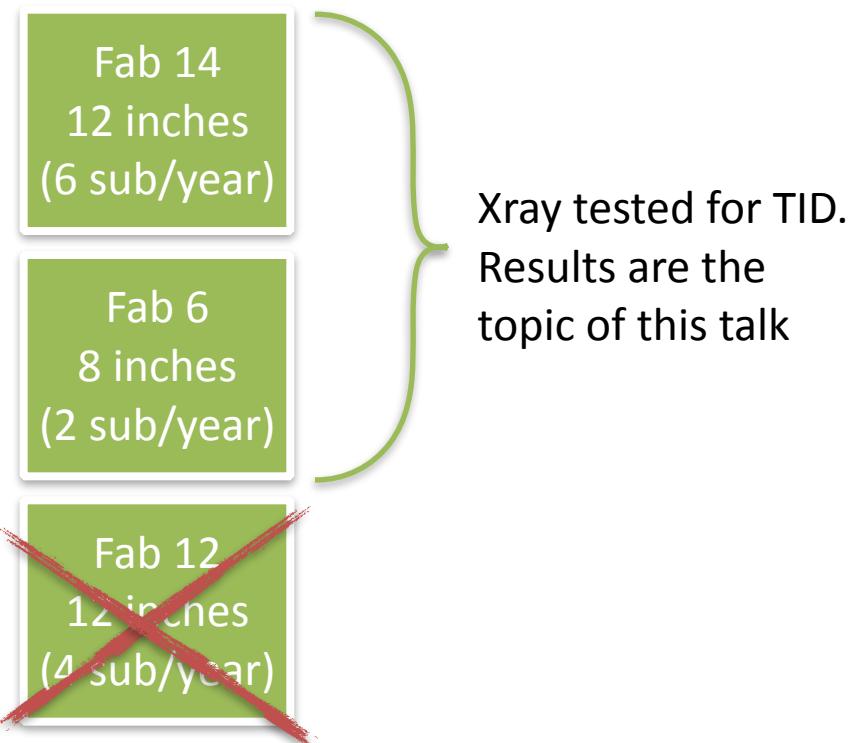
Fab 14  
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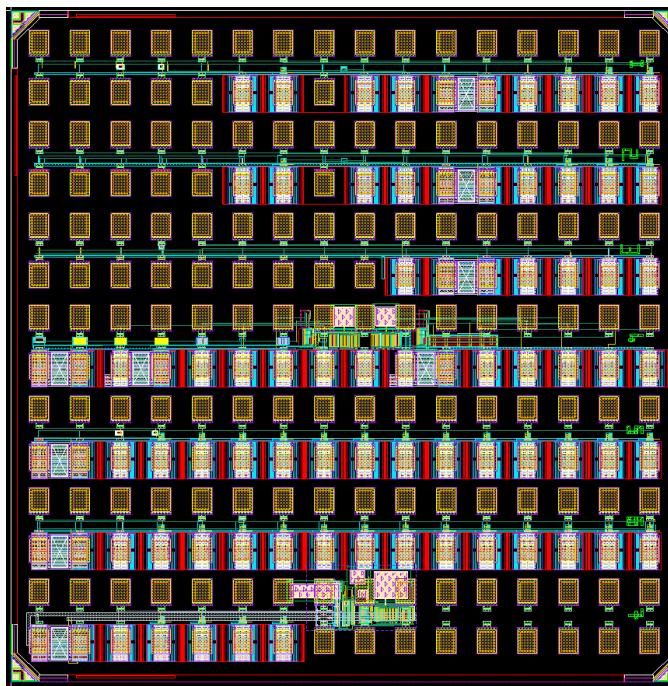
Fab: semiconductor fabrication plant

# The new 130nm technology has different fabs



Fab: semiconductor fabrication plant

TID\_CHIP



NMOS\_core

PMOS\_core + diode

IO

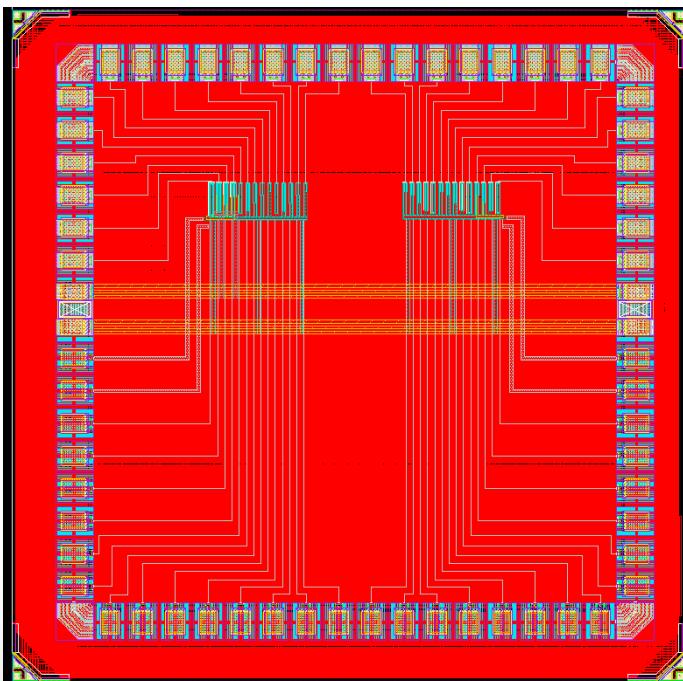
FoxFet + res

NMOS\_core

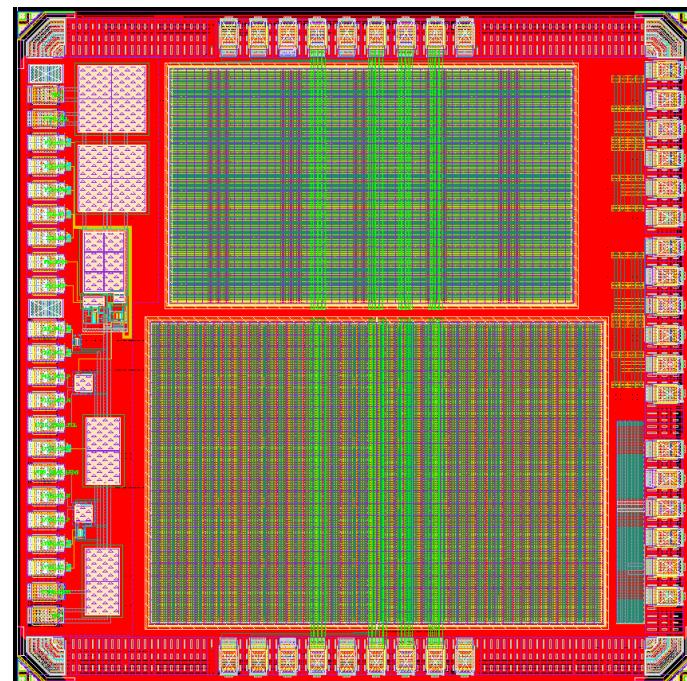
PMOS\_core

BGP

Noise\_CHIP



Digital\_CHIP



Thanks to Xavi and  
the colleagues in  
Cracow for their help  
(Marek, Mirek and  
Tomek)

# Several devices are included in the TID\_chip

Core transistors (NMOS and PMOS) rated for 1.2V with different flavors  
(high V<sub>th</sub>, low V<sub>th</sub> and regular)

IO transistors (NMOS and PMOS) rated for 2.5V

Diodes: p in Nwell, DTNMOS and DTPMOS

Foxfet

Additionally a first version of a Bandgap based on DTNMOS has been included

## TID: Total Ionizing Dose

Legacy technology has been tested up to TID=100Mrad with a dose rate  $\sim 1.5\text{Mrad/h}$ , at **25C**.

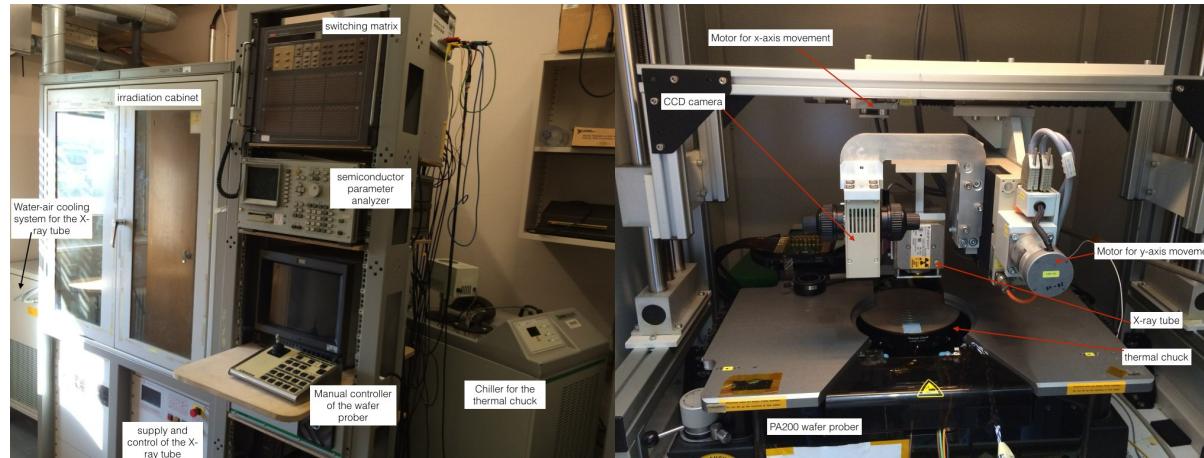
The new technology has been tested up to TID=400Mrad at **25C** and **-30C**

2 dose rates used: high dose rate (HDR)  $\sim 9\text{Mrad/h}$  (200Mrad/day)

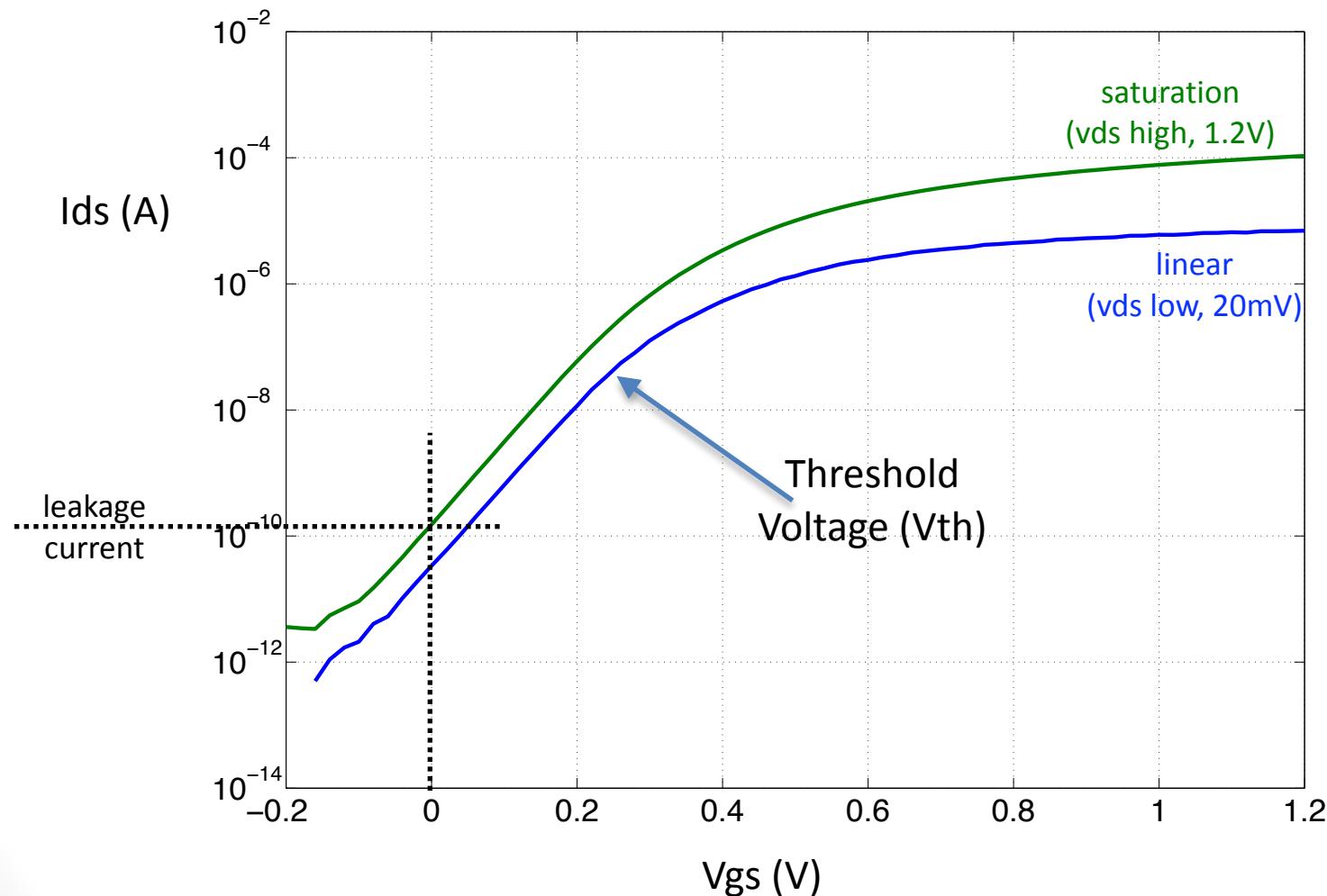
low dose rate (LDR)  $\sim 90\text{Krad/h}$  (2Mrad/day)

dose rate for LHCb Velopix application: 0.2Mrad/day (400Mrad over 10years, assuming 200 beam days/year)

Irradiation condition:

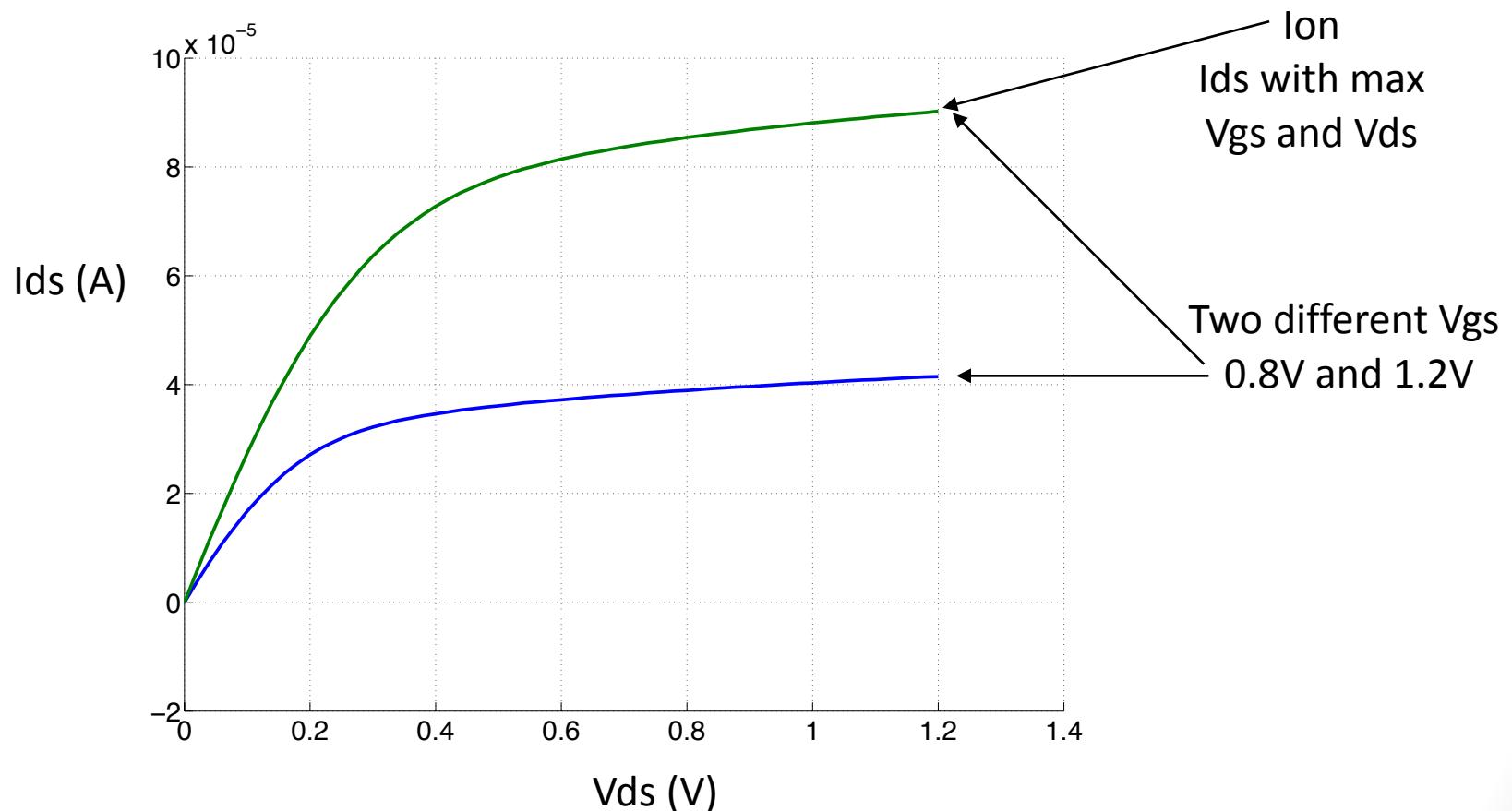


# A small reminder... $Id \propto Vg$



NB: real measurement

# A small reminder... $I_d V_d$



NB: real measurement

# Outcome of the test

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GOOD NEWS!

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GOOD NEWS!

The new 130nm technology from Fab6 is performing better than legacy 130nm technology in term of intrinsic TID tolerance.

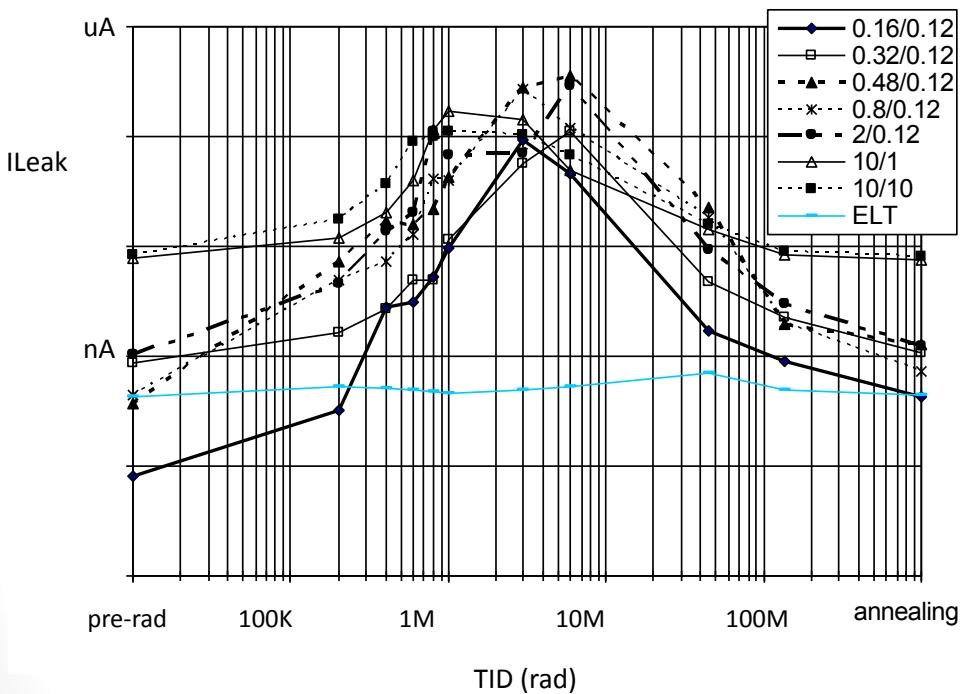
It can be therefore considered as a valid alternative.

For Fab14 there are differences for the NMOS.

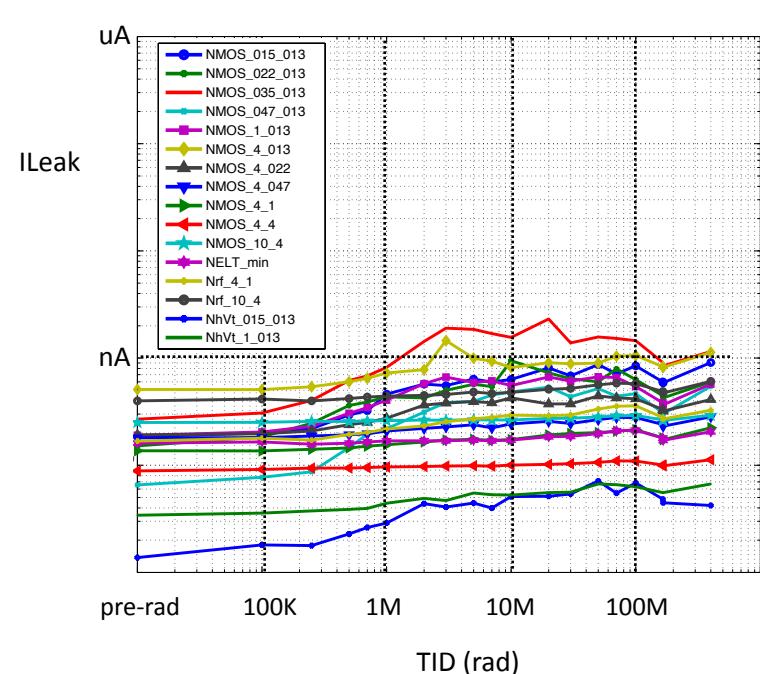
NMOS Core, 1.2V

NMOS leakage current increase is limited

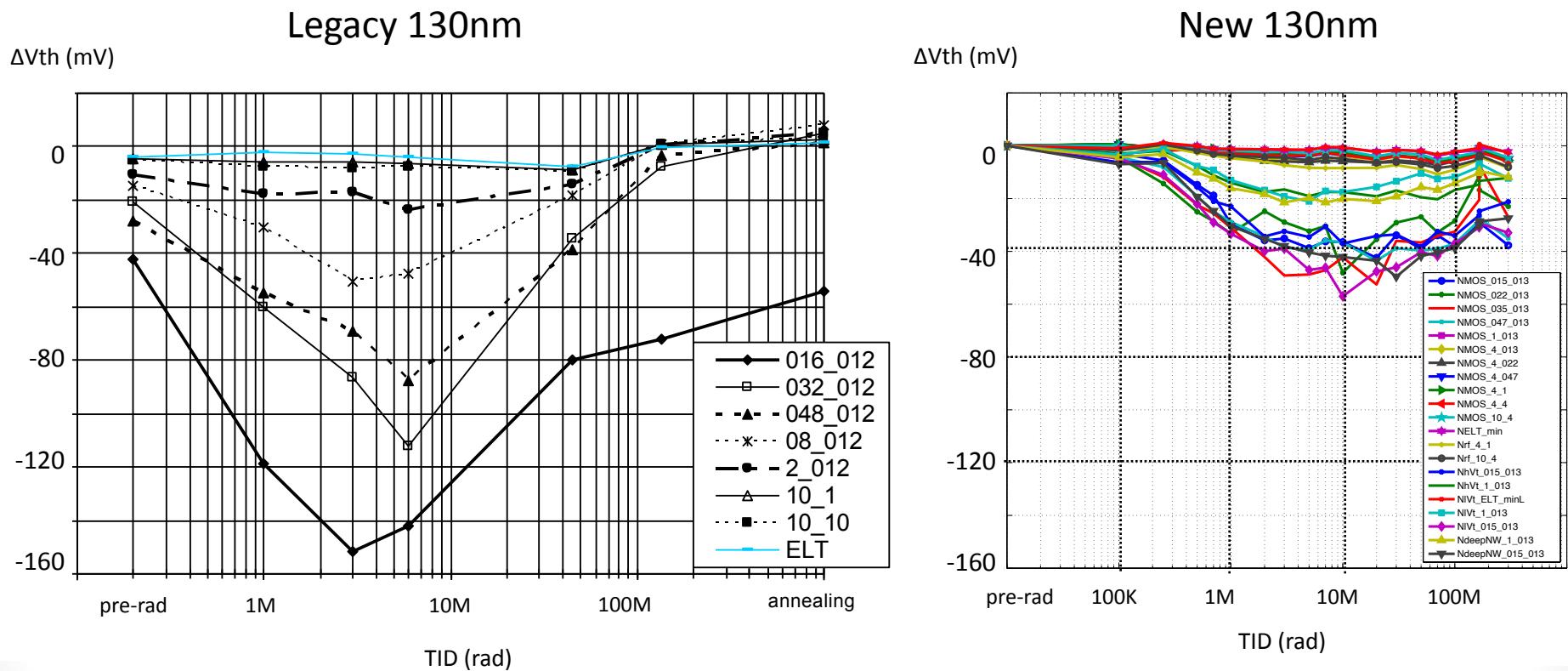
# Legacy 130nm



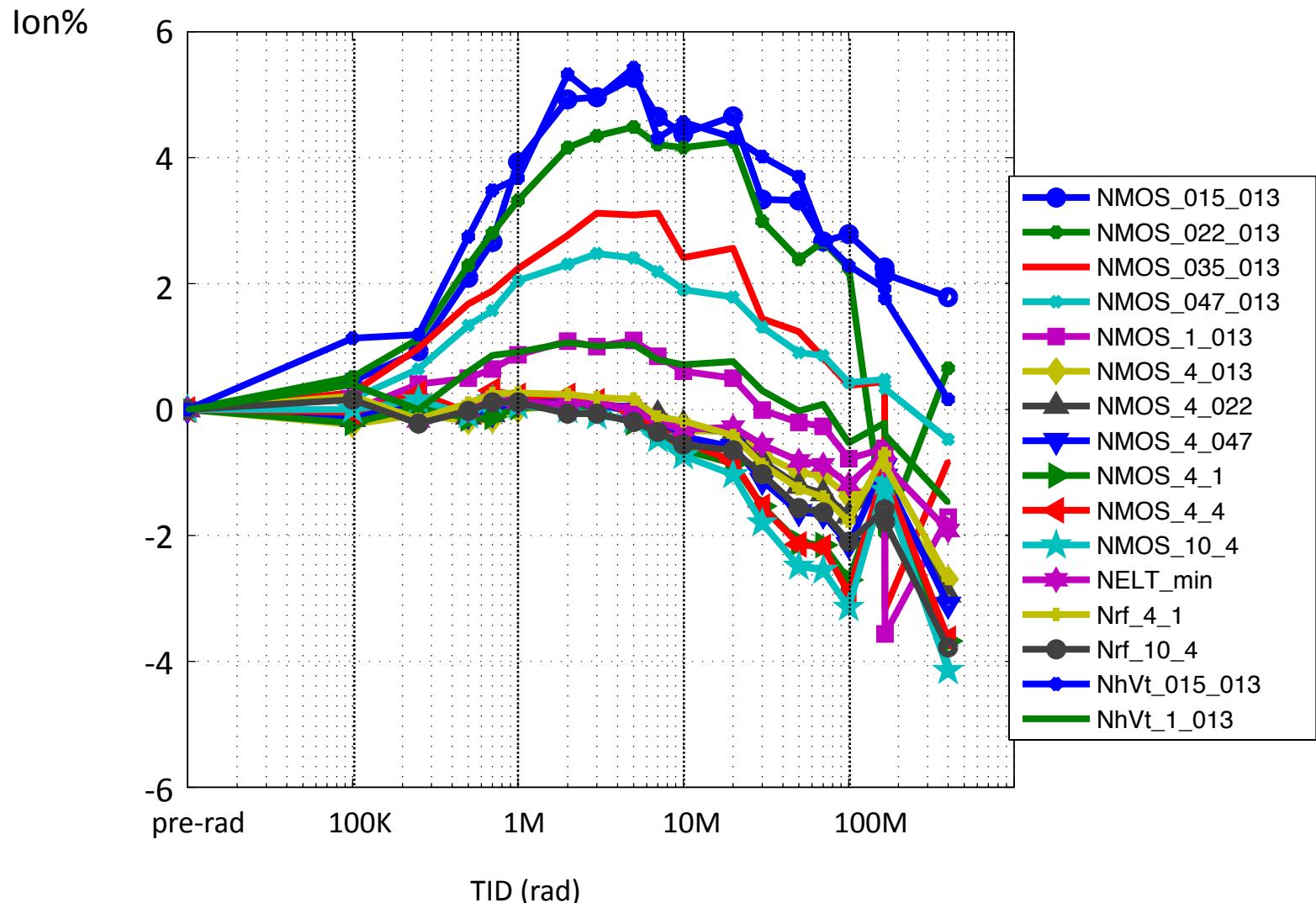
## New 130nm



# NMOS V<sub>th</sub> shift is below 50mV

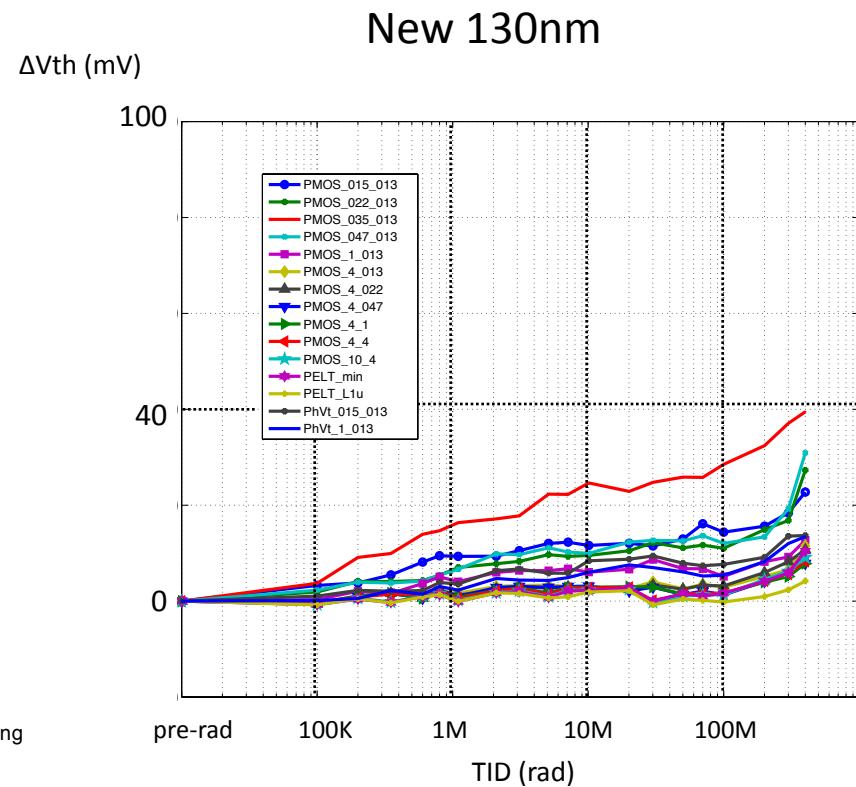
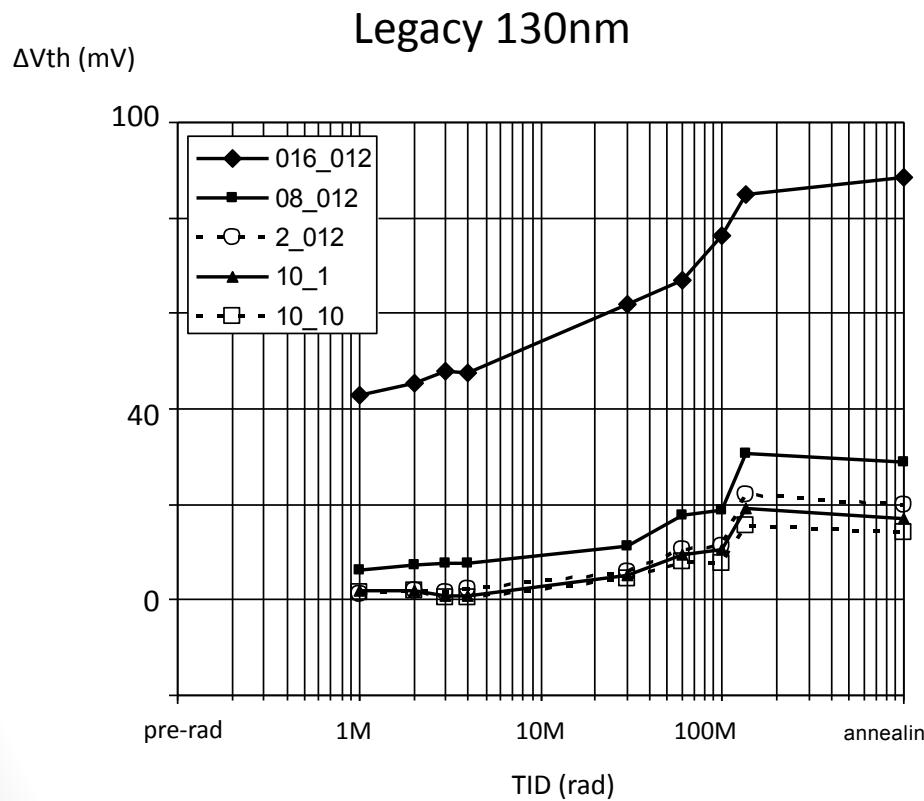


# NMOS Ion degradation is limited

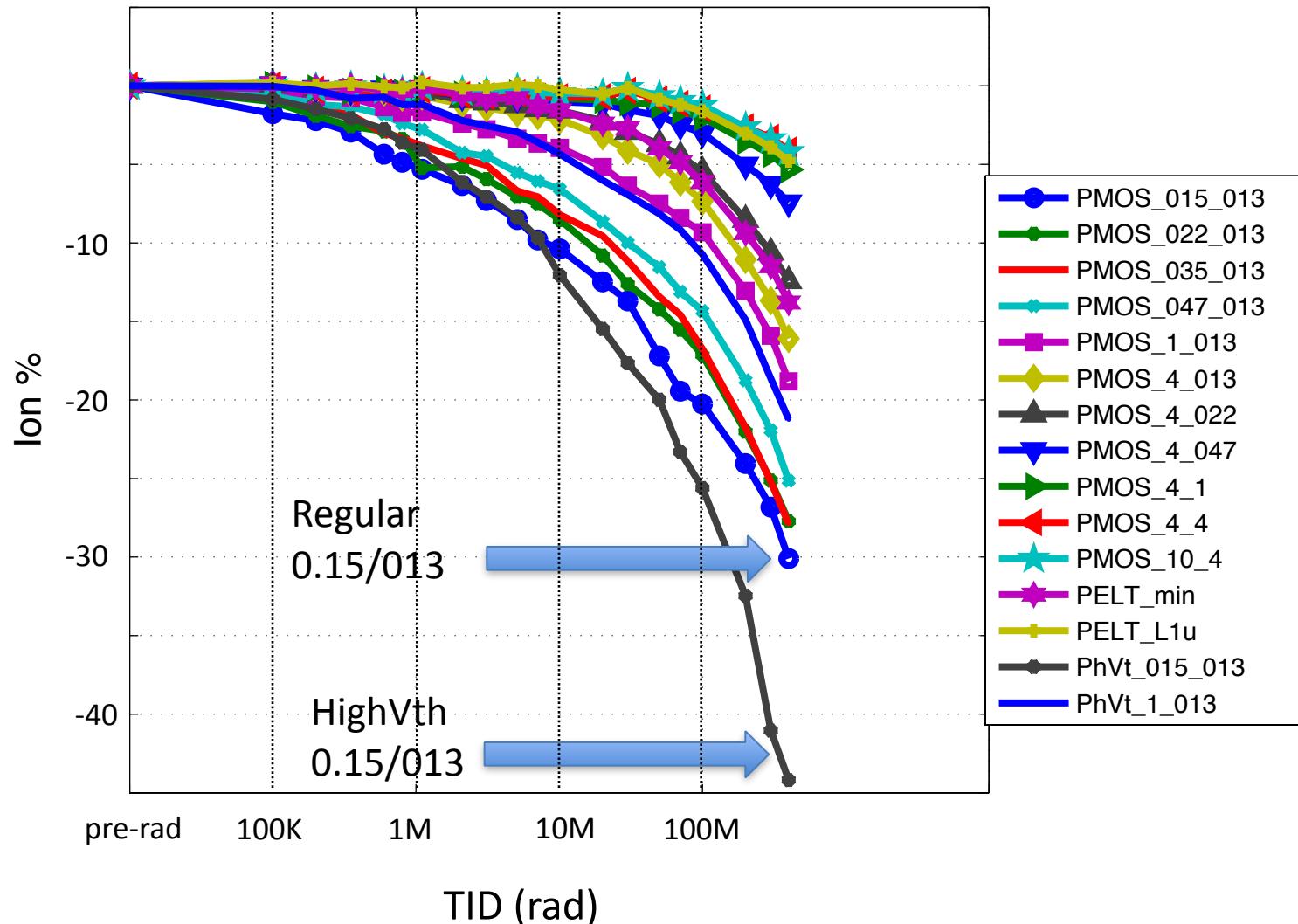


PMOS Core, 1.2V

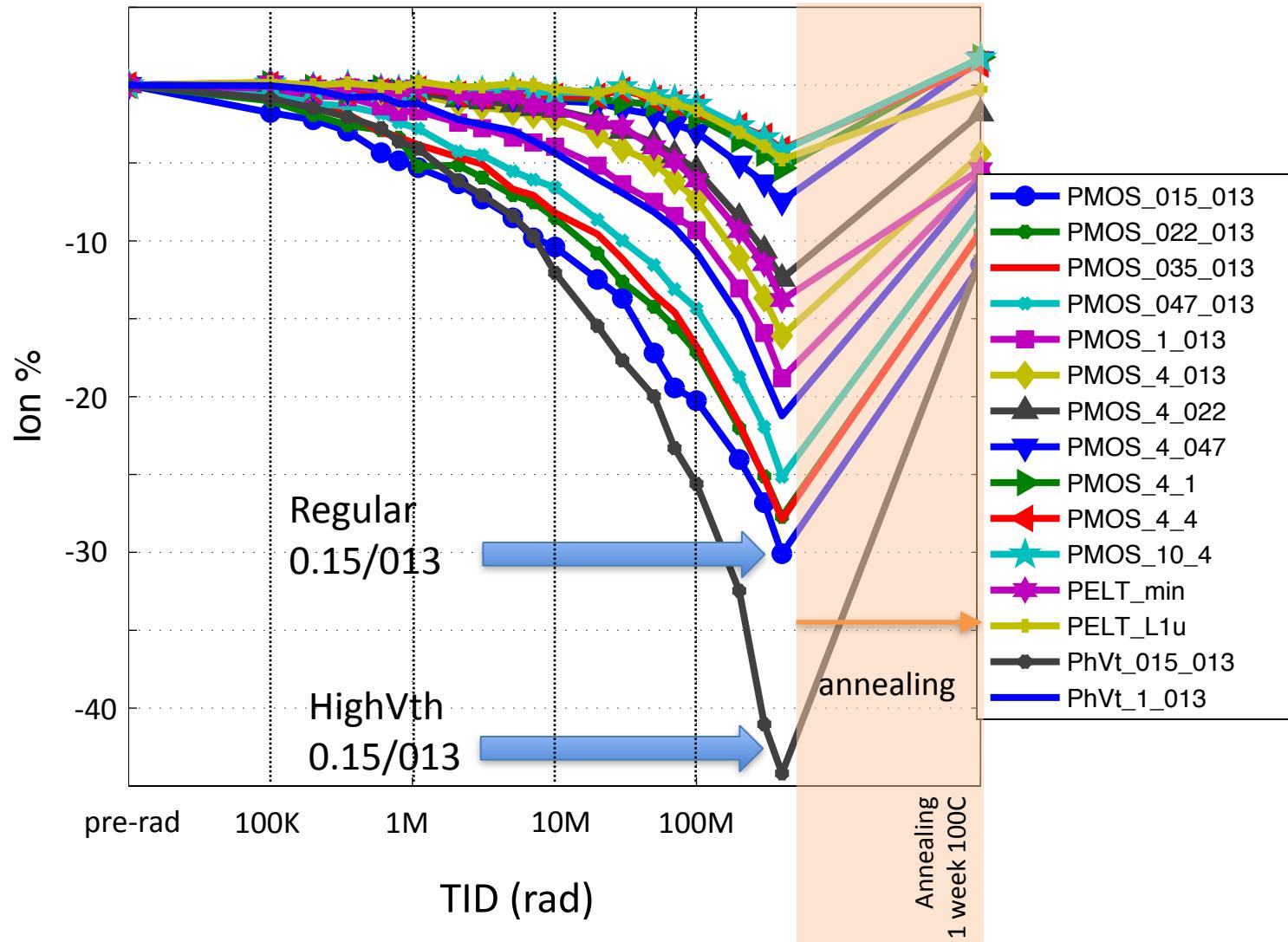
# PMOS V<sub>th</sub> shift is below 40mV



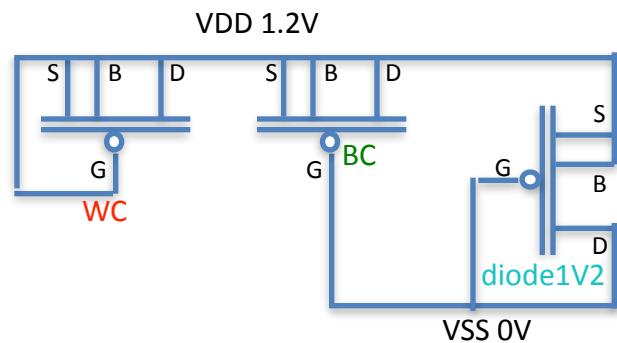
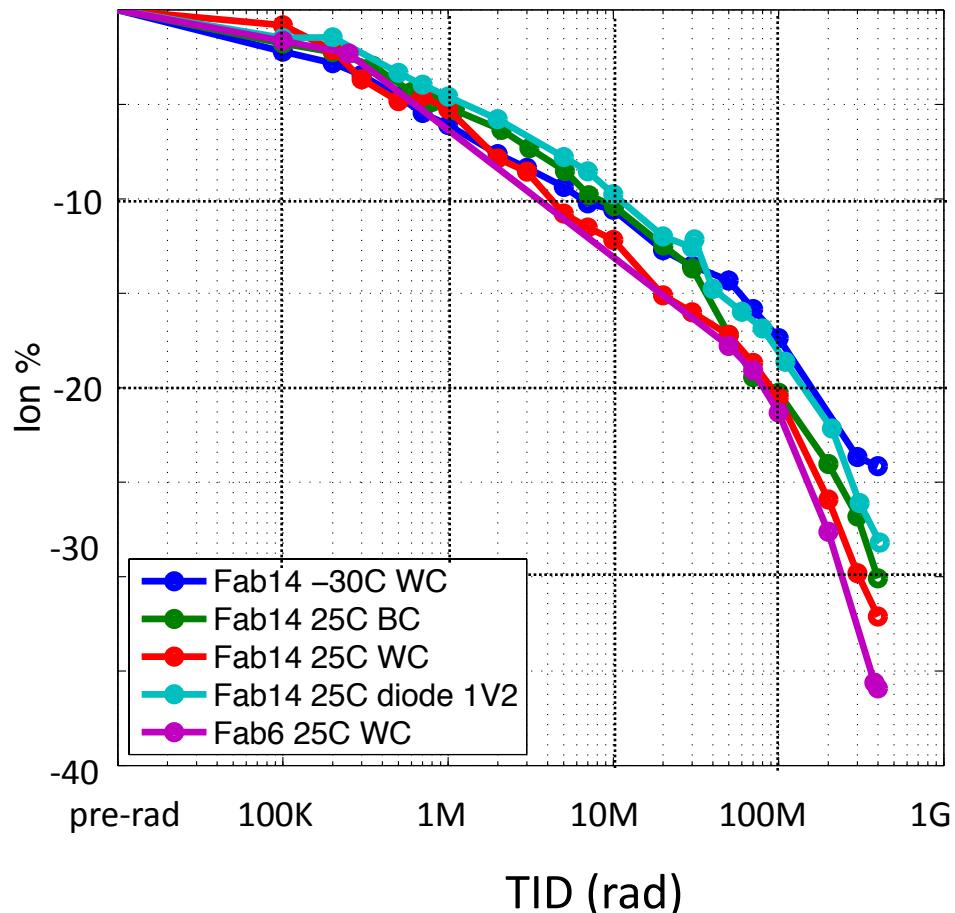
The PMOS Ion degradation is large starting from 100Mrad



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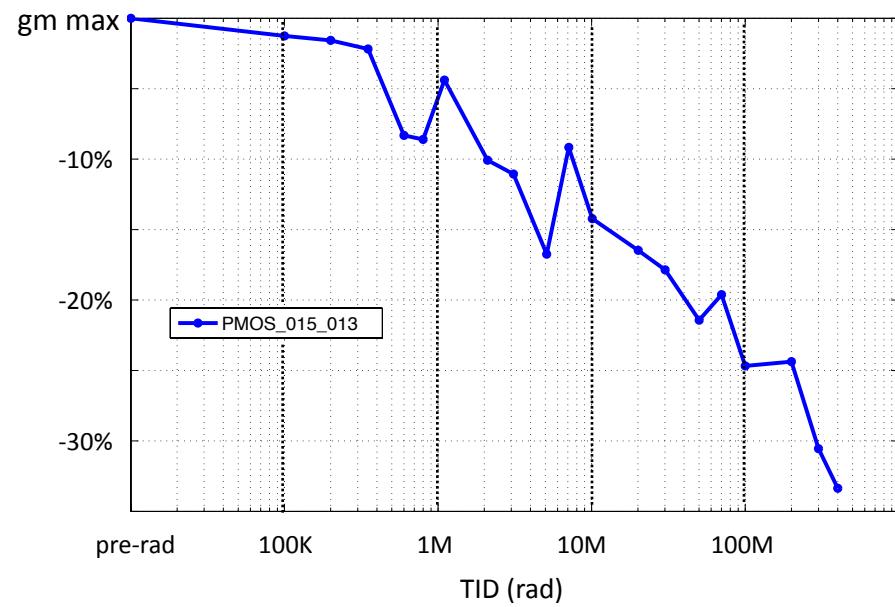
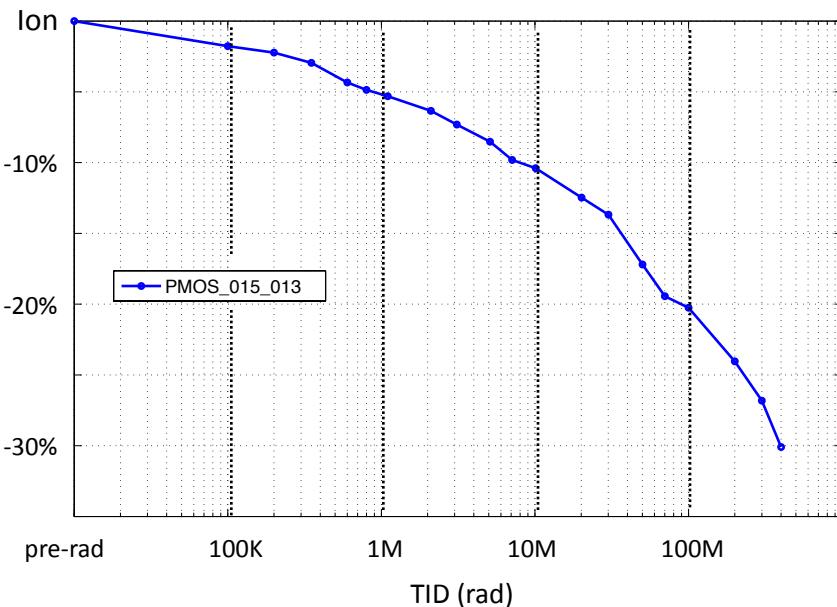


The Ion degradation is similar in all fabs.  
A little better at -30C



PMOS min size  
0.15/0.13

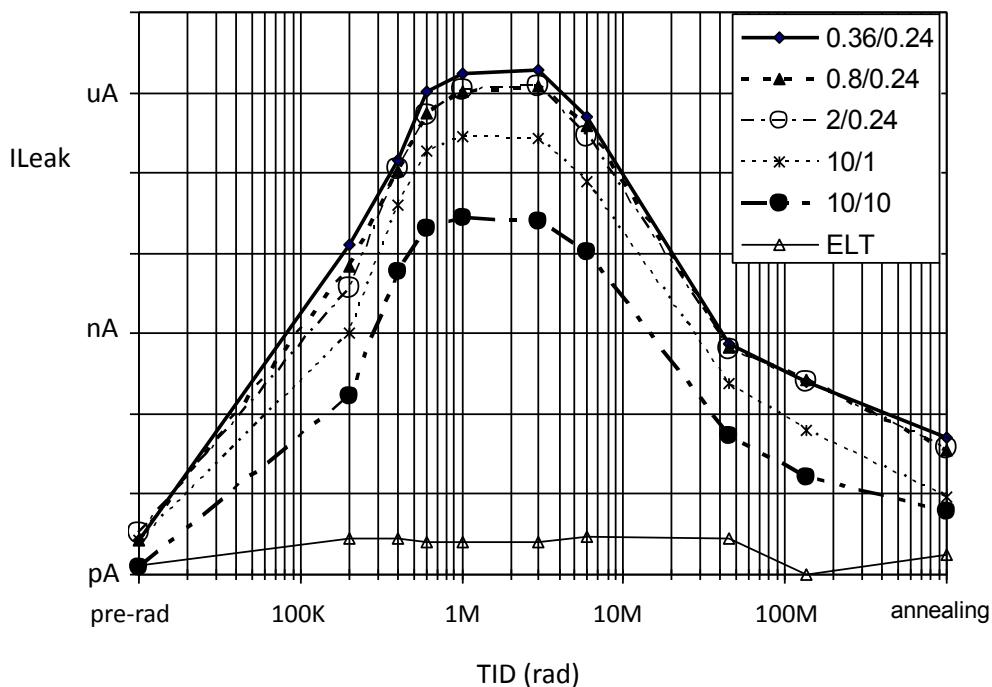
# The Ion degradation is mainly related to gm degradation



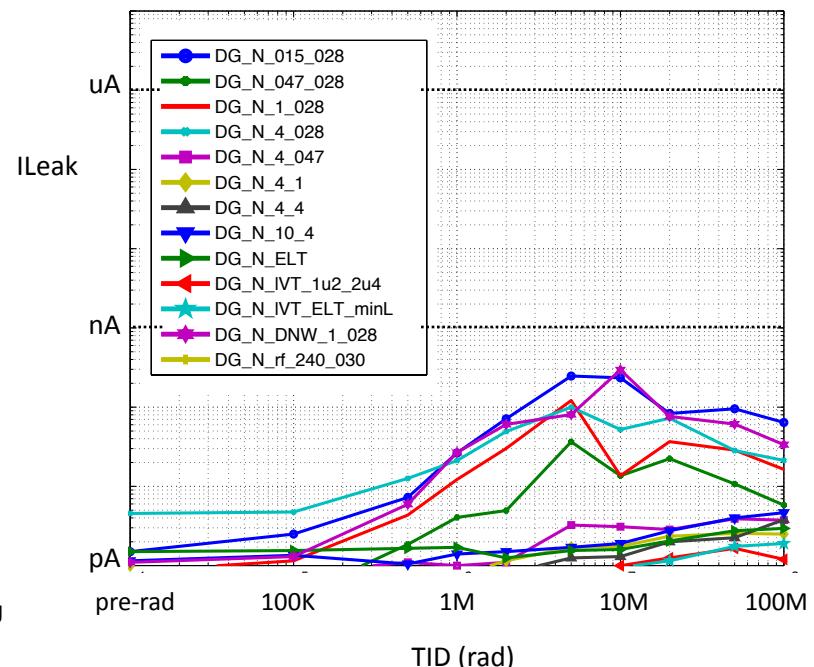
NMOS I/O, 2.5V

# I/O NMOS Leakage current is below nA

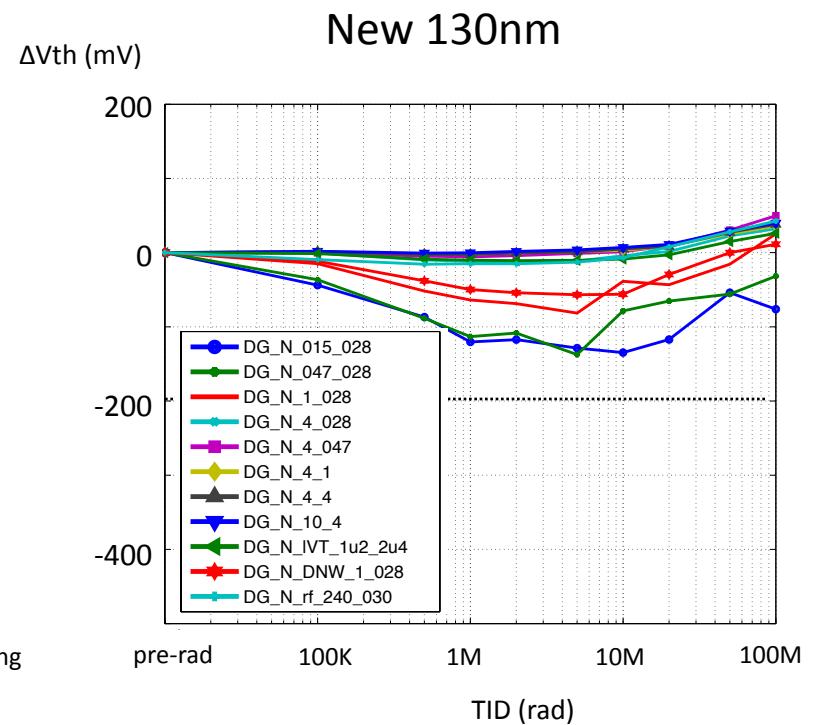
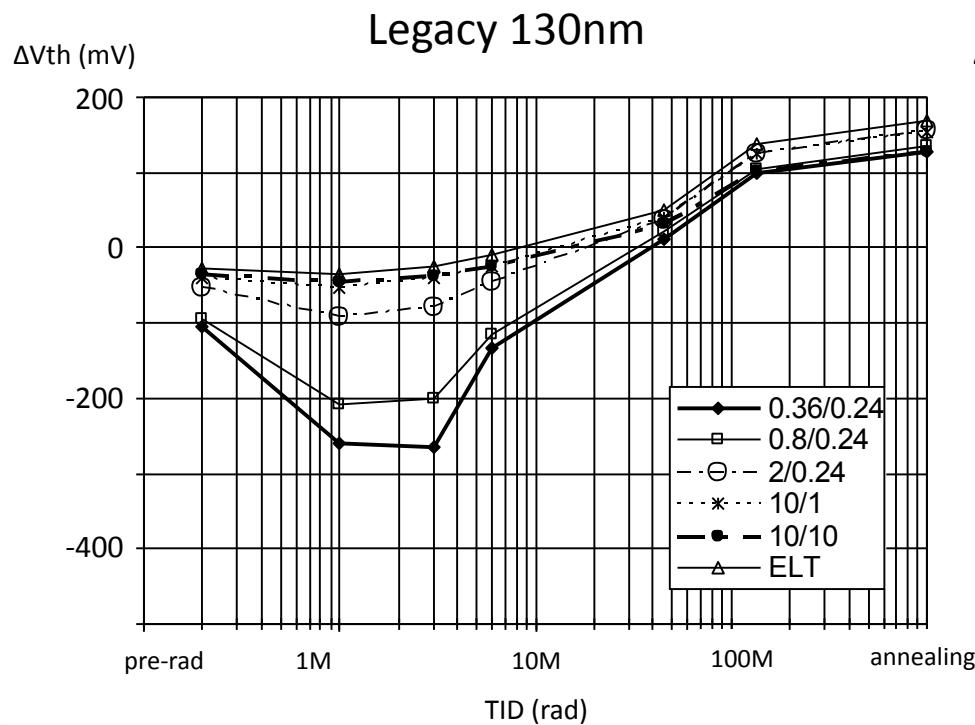
Legacy 130nm



New 130nm

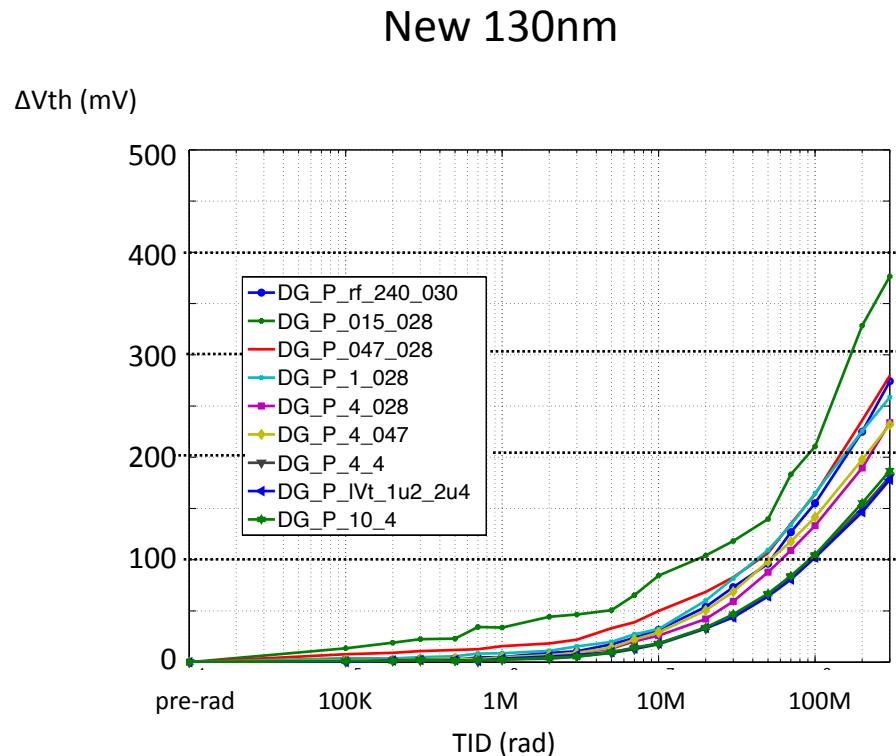
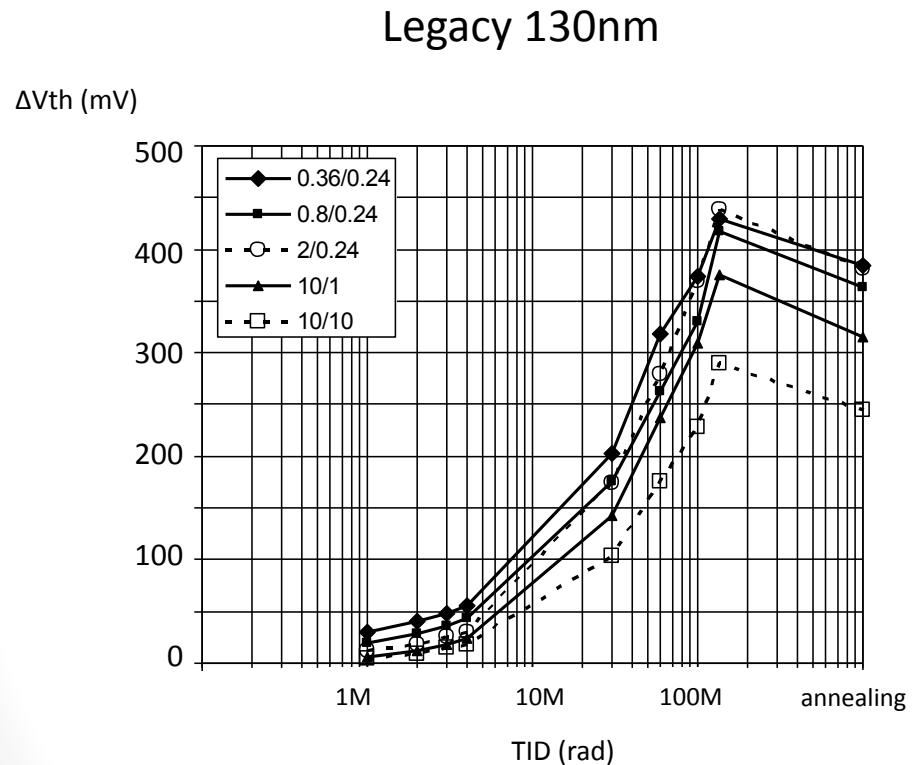


# I/O NMOS V<sub>th</sub> shift is below 200mV



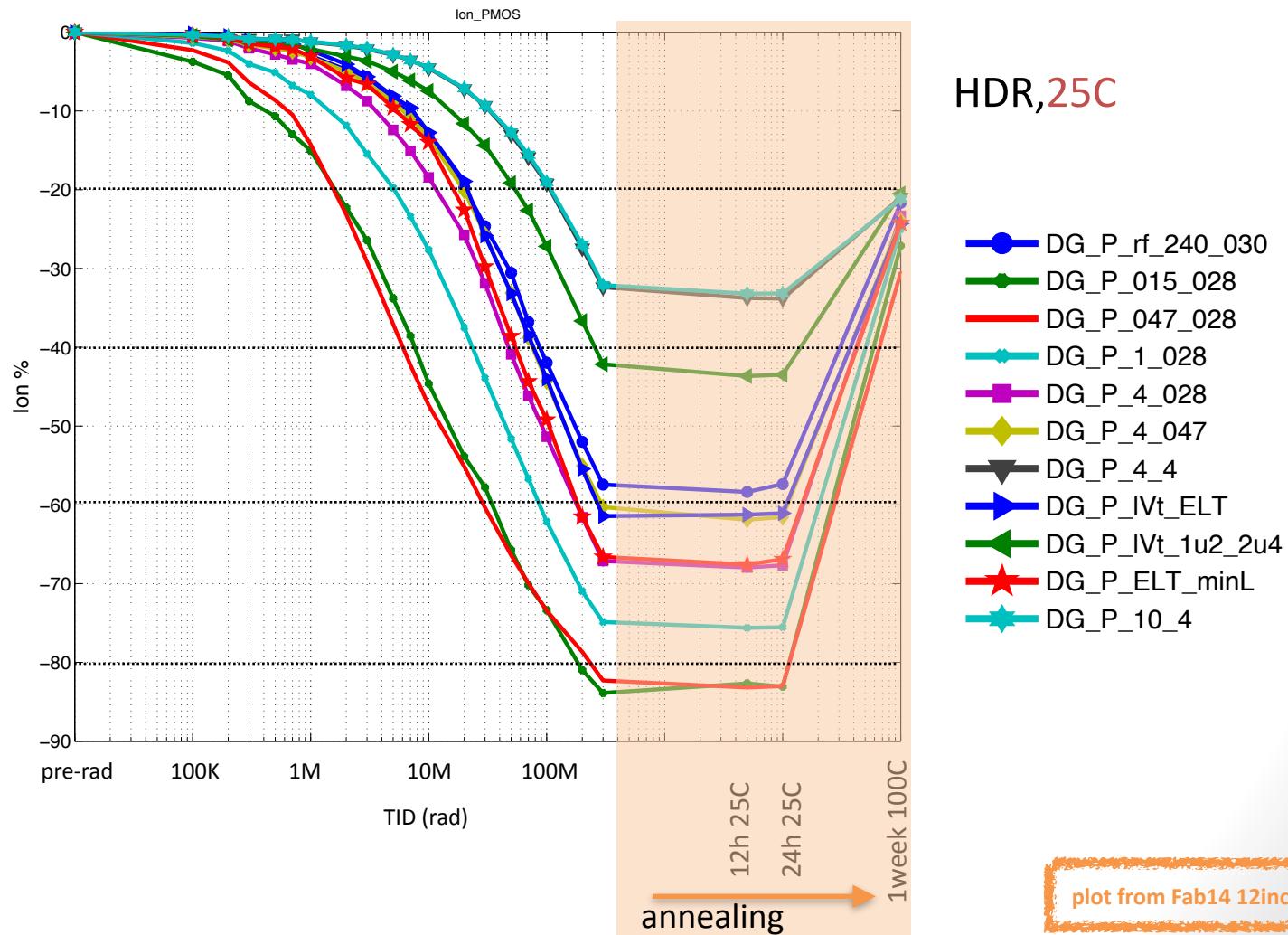
PMOS I/O, 2.5V

# I/O PMOS V<sub>th</sub> shift



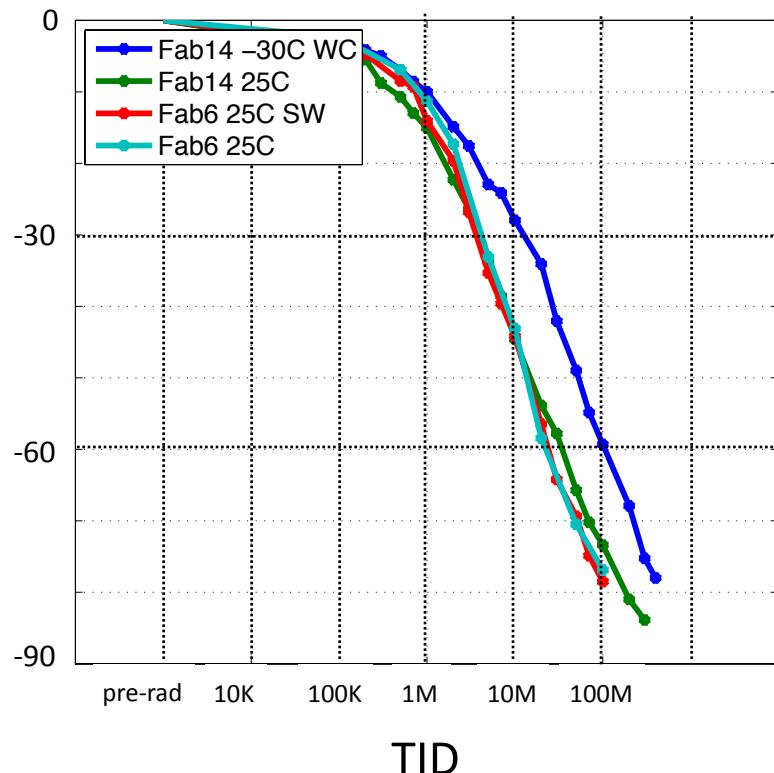
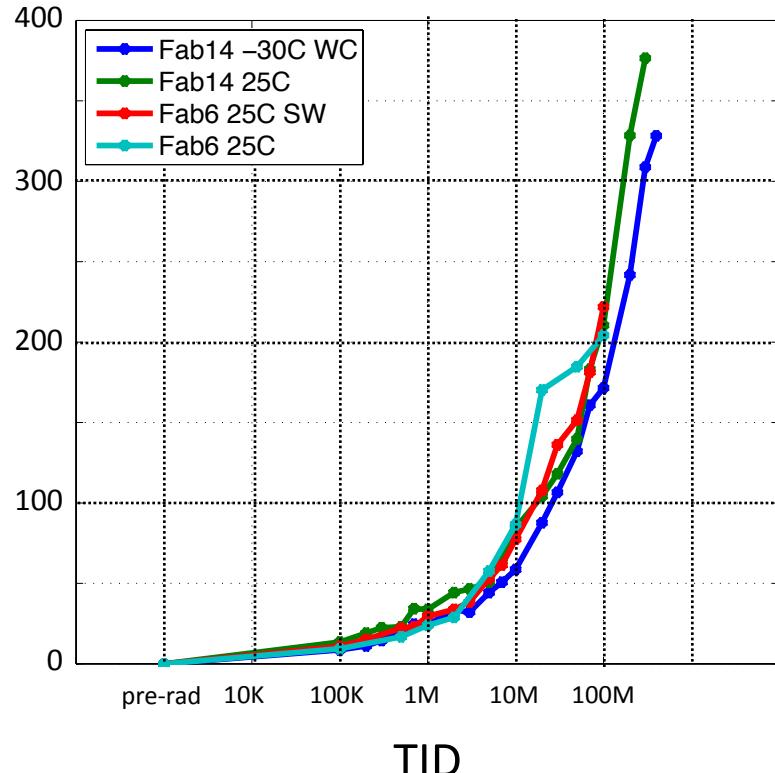
# I/O PMOS Ion degradation is severe

At 400 Mrad it reaches -80% for small size transistors. Also ELT PMOS shows an important degradation (-68%). Only after an annealing of 1week at 100C there is a recovery of the Ion. There are no big differences at **-30C**.



# Difference between Fabs, temperature and bias condition

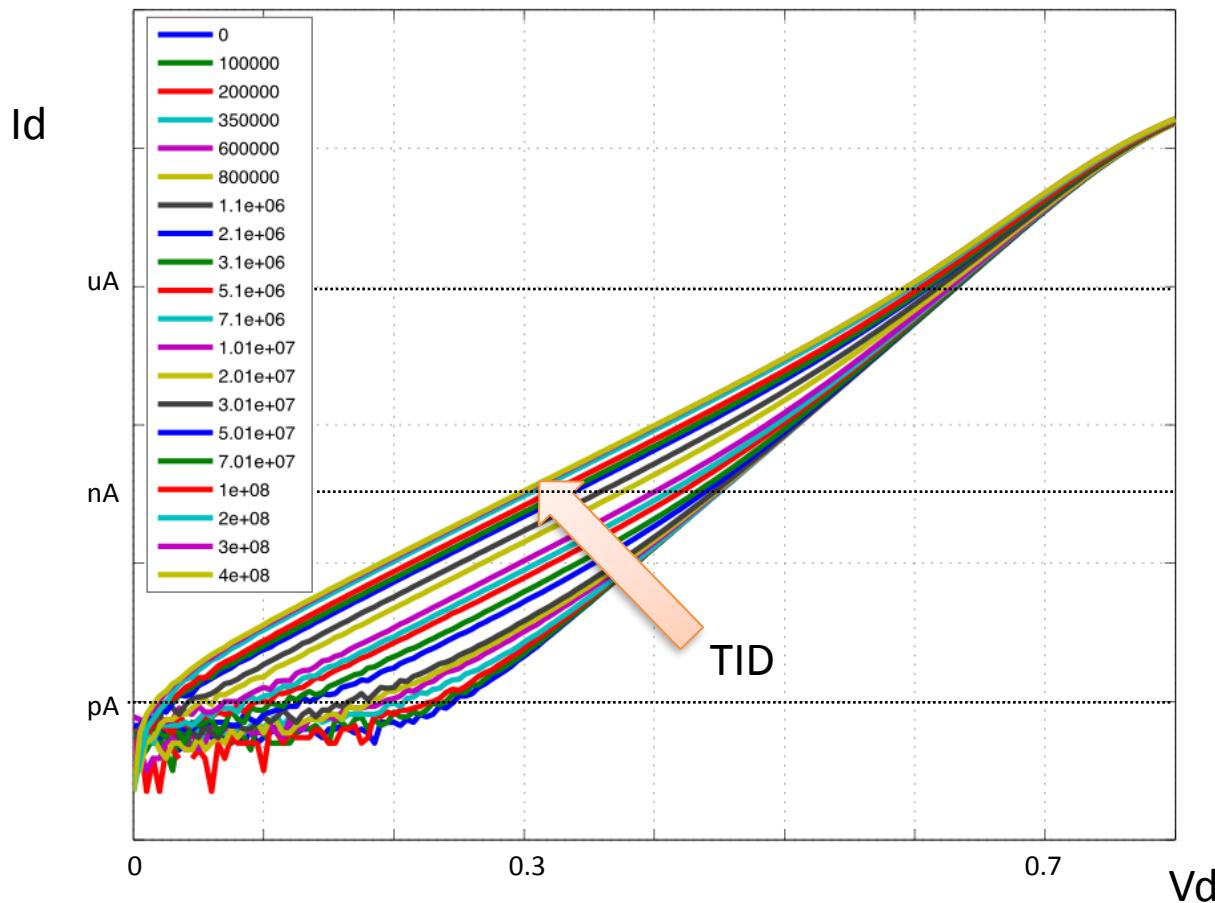
Ion%

 $\Delta V_{th}$  (mV)

I/O PMOS min size  
0.15/0.28

# Diodes

# IdVd degradation

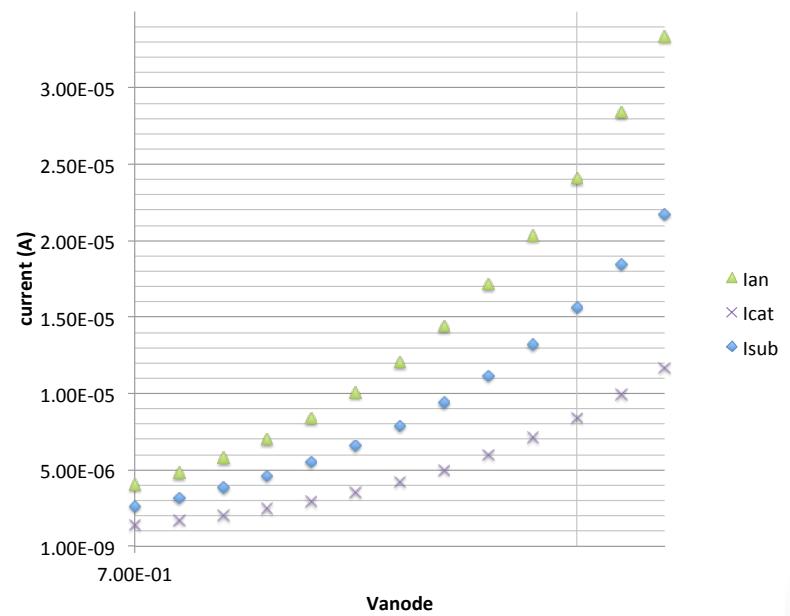
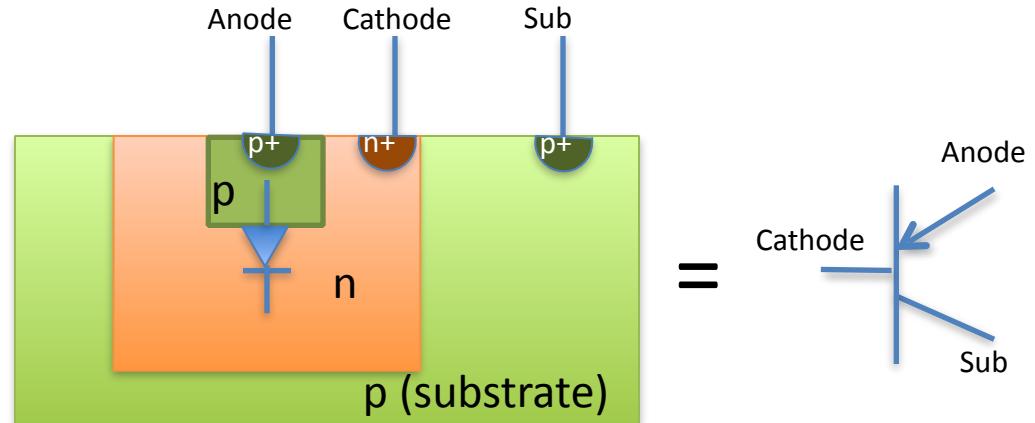
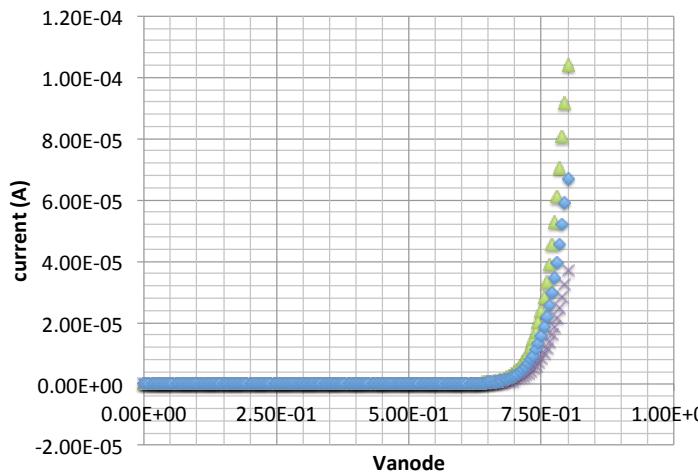


All the p in NW diodes suffer of a large leakage current which makes them difficult to be used for Bandgap application.

# Not really diodes, but pnp!

P-in-NW diodes are in reality part of a bipolar parasitic structure (pnp) with a certain gain.

Plotting the I vs Vanode for the three terminals it appears that  $I_{cathode} \ll I_{anode}$  and even more important  $I_{sub} > I_{cathode}$ .



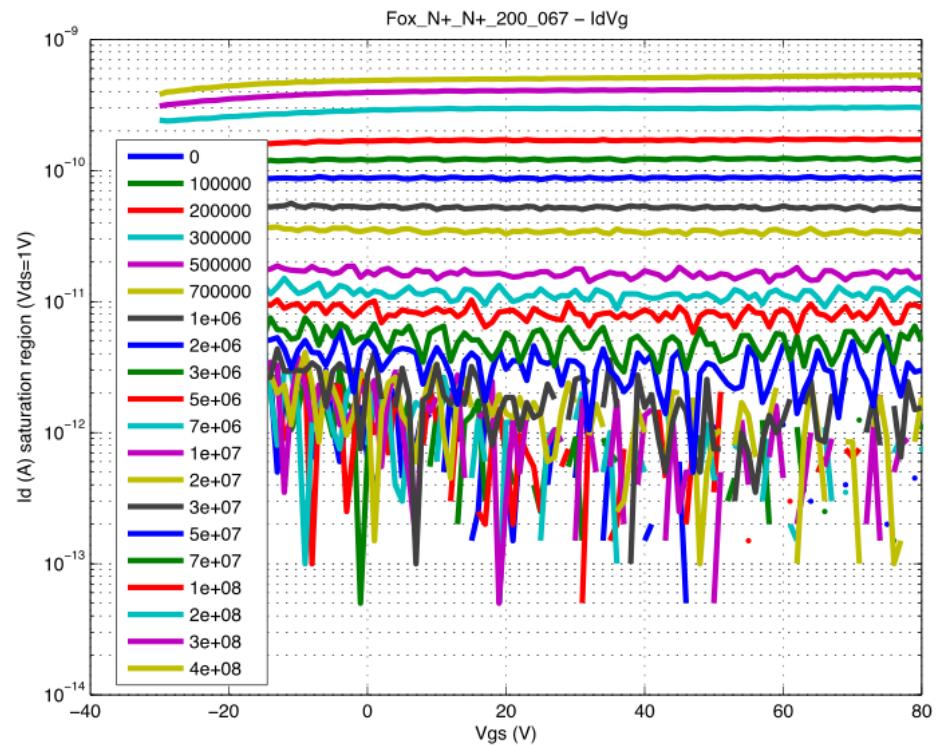
**FOXFET**

# FOXFET

5 FOXFETs (field oxide transistors) have been tested to see the leakage current between devices.

The FOXFETs are:

- N+ N+ ( $W/L=200/0.67$ )
- N+ Nwell ( $W/L=200/0.32$ )
- N+ Nwell ( $W/L=200/0.6$ )
- Nwell Nwell ( $W/L=200/1$ )
- Nwell Nwell ( $W/L=200/1.48$ )



The increase of leakage current is negligible therefore there is no indication of need of guard rings.

# Summary of the results

GOOD NEWS!

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It can be therefore considered as a valid alternative.

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BUT... For Fab14 (12 inches) there are differences for the NMOS.

# Differences between Fabs

PMOS (core and I/O) and diodes from Fab6 and Fab14 show the same degradation

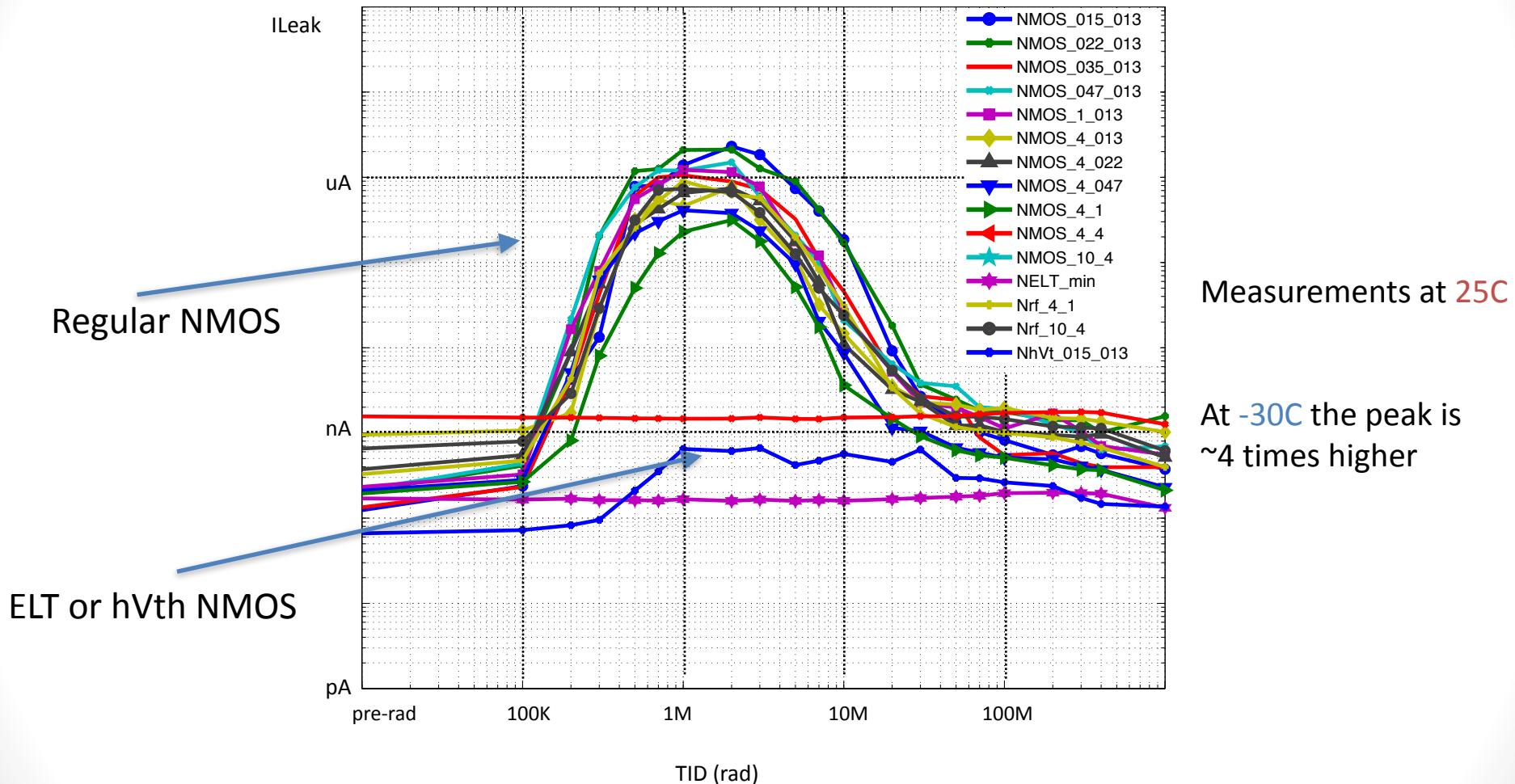
NMOS (core and I/O) from the two Fabs show very different behavior:

Fab6 do not show increase of leakage current

Fab14 have large increase of the leakage current, but the annealing time is fast

# NMOS Core and I/O

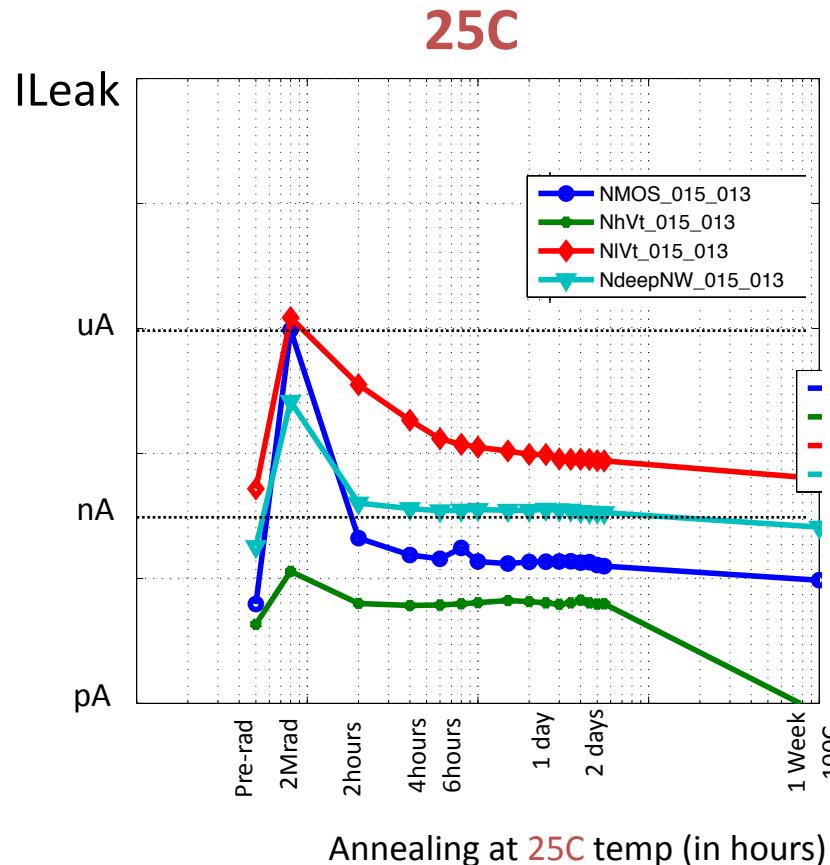
# NMOS Leakage current for Fab14



# NMOS Leakage current with annealing

The aim is the understanding of the annealing behavior at **25C** and **-30C**

Procedure:      irradiation up to 2 Mrad (highest peak)  
 annealing for 48 hours with 2-5h delay between measurements

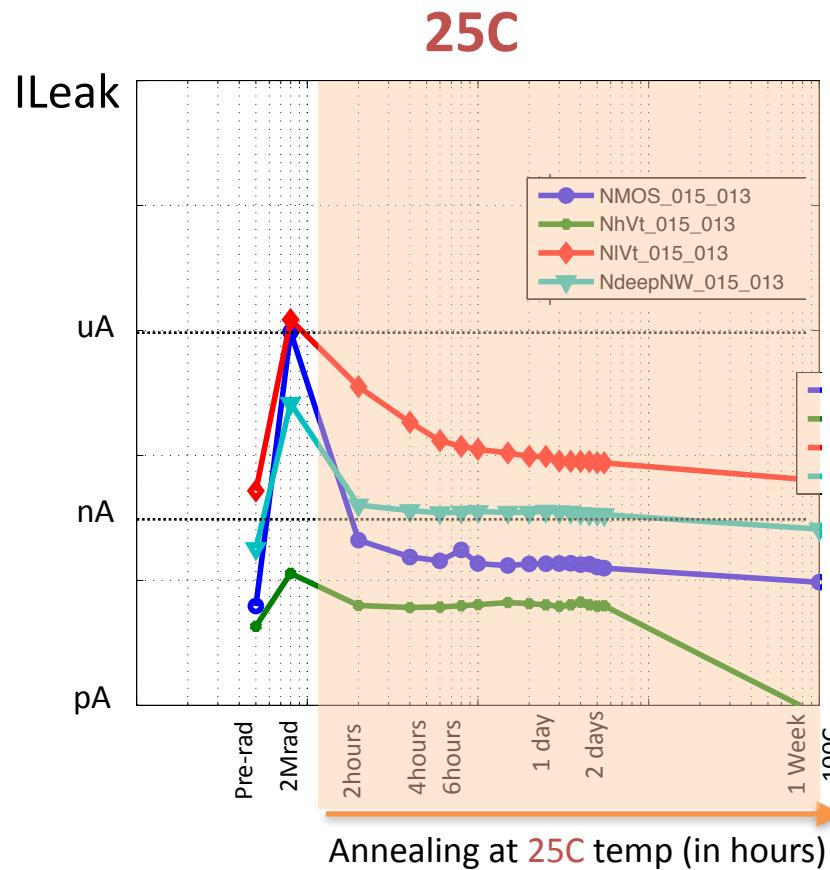


Annealing time:  
 at **25C** is ~hours  
 at **-30C** is ~days

# NMOS Leakage current with annealing

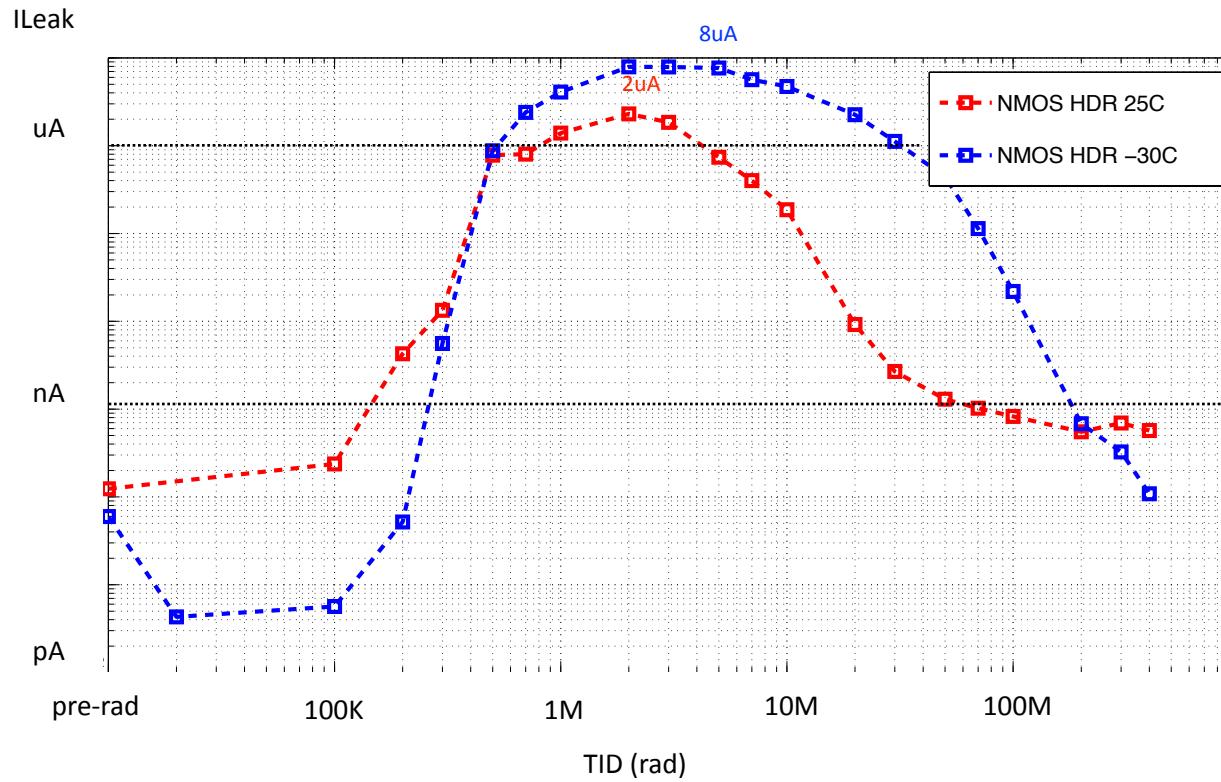
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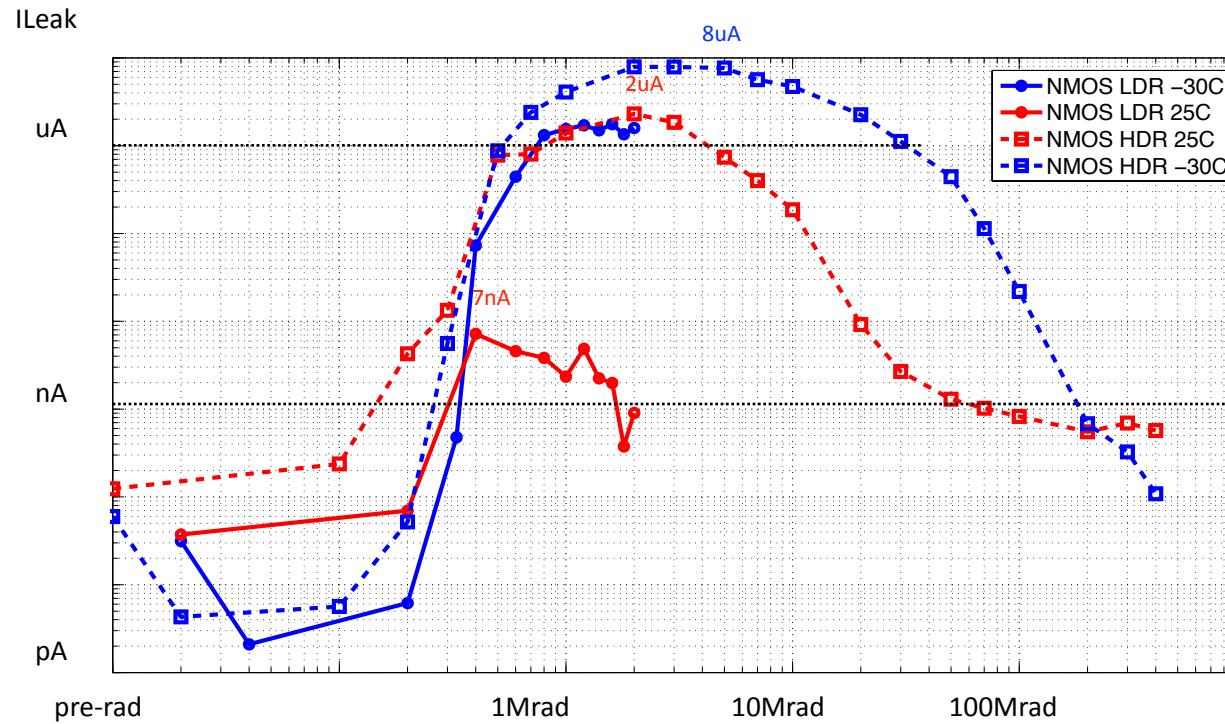
Annealing time:  
 at **25C** is ~hours  
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# Differences between irradiation T



high dose rate (HDR)  $\sim 9\text{Mrad/h}$  (200Mrad/day)

# Differences between irradiation T and Dose Rates

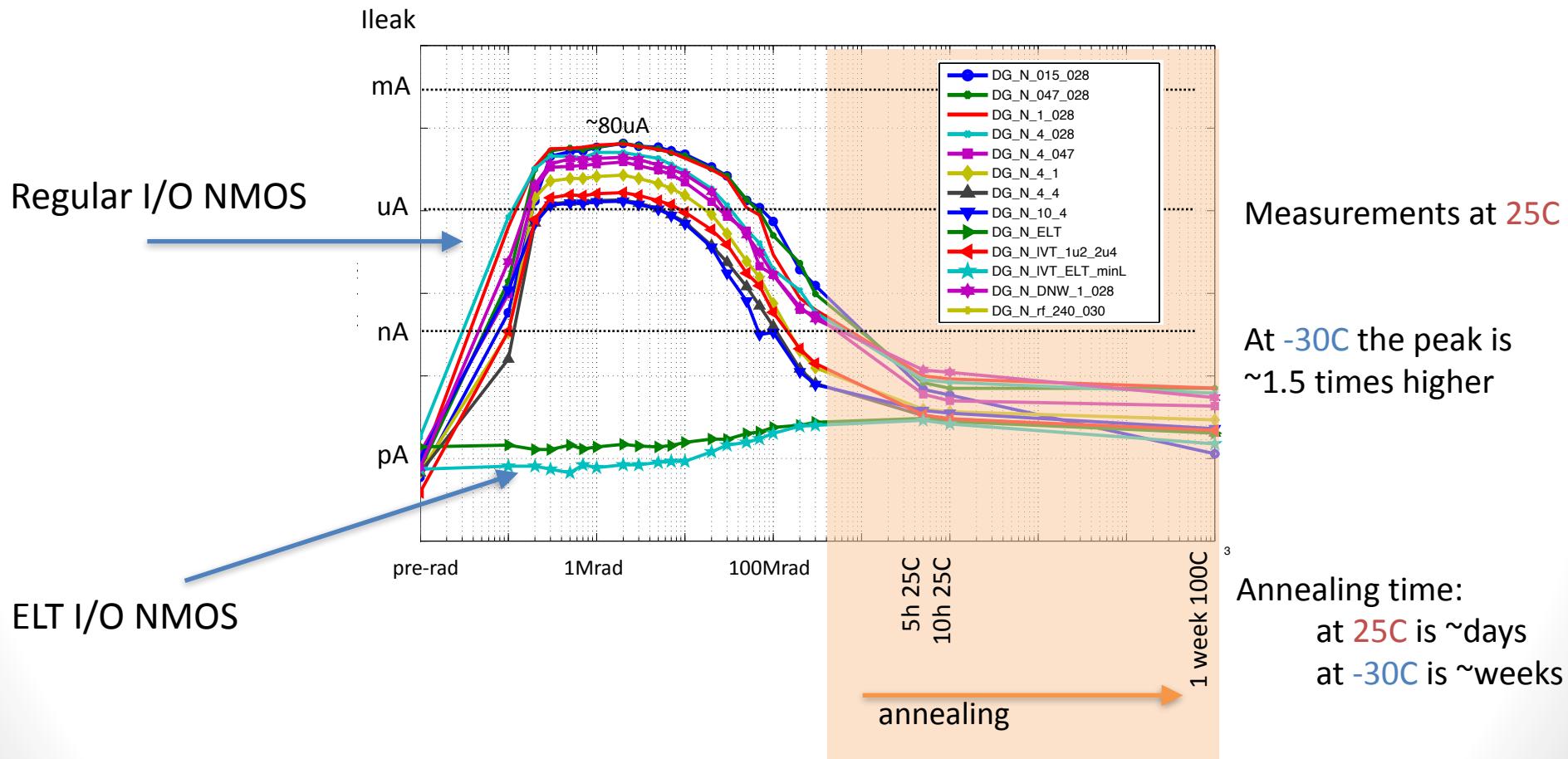


high dose rate (HDR)  $\sim 9\text{Mrad/h}$  ( $200\text{Mrad/day}$ )

low dose rate (LDR)  $\sim 90\text{Krad/h}$  ( $2\text{Mrad/day}$ )

dose rate for LHCb Velopix application:  $0.2\text{Mrad/day}$  ( $400\text{Mrad}$  over 10years, assuming 200 beam days/year)

# I/O NMOS Leakage current



# Conclusions

The new 130nm technology from Fab6 (8 inches) is performing better than legacy 130nm technology in term of intrinsic TID tolerance.

The new 130nm technology from Fab14 (12 inches) shows:

- same performance for PMOS

- large increase of leakage current for NMOS, but

  - annealing time is fast and  $I_{leak}$  decreases with dose rate

  - $hV_{th}$  and ELT layout should be used if leakage is a concern

Therefore for production the best choice is Fab6.

For prototyping Fab14 can be used, knowing that during TID tests (with very high dose rate) the ASICs may suffer of the increase of leakage current

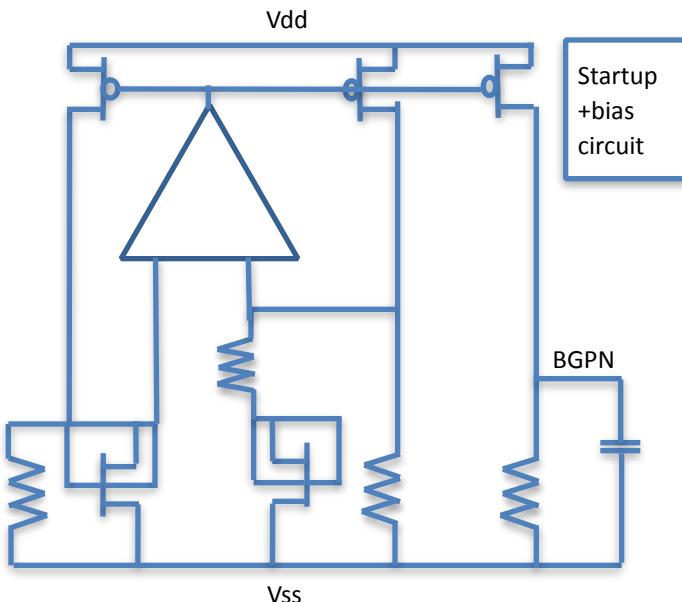
# BANDGAP

# Bandgap Information

Based on DTNMOS, it provides  $BGPN \approx 285mV$

Total  $I_{dd}$  current (at  $V_{dd}=1.2V$ ) =  $90\mu A$

Layout dimensions  $160\mu m \times 320\mu m$

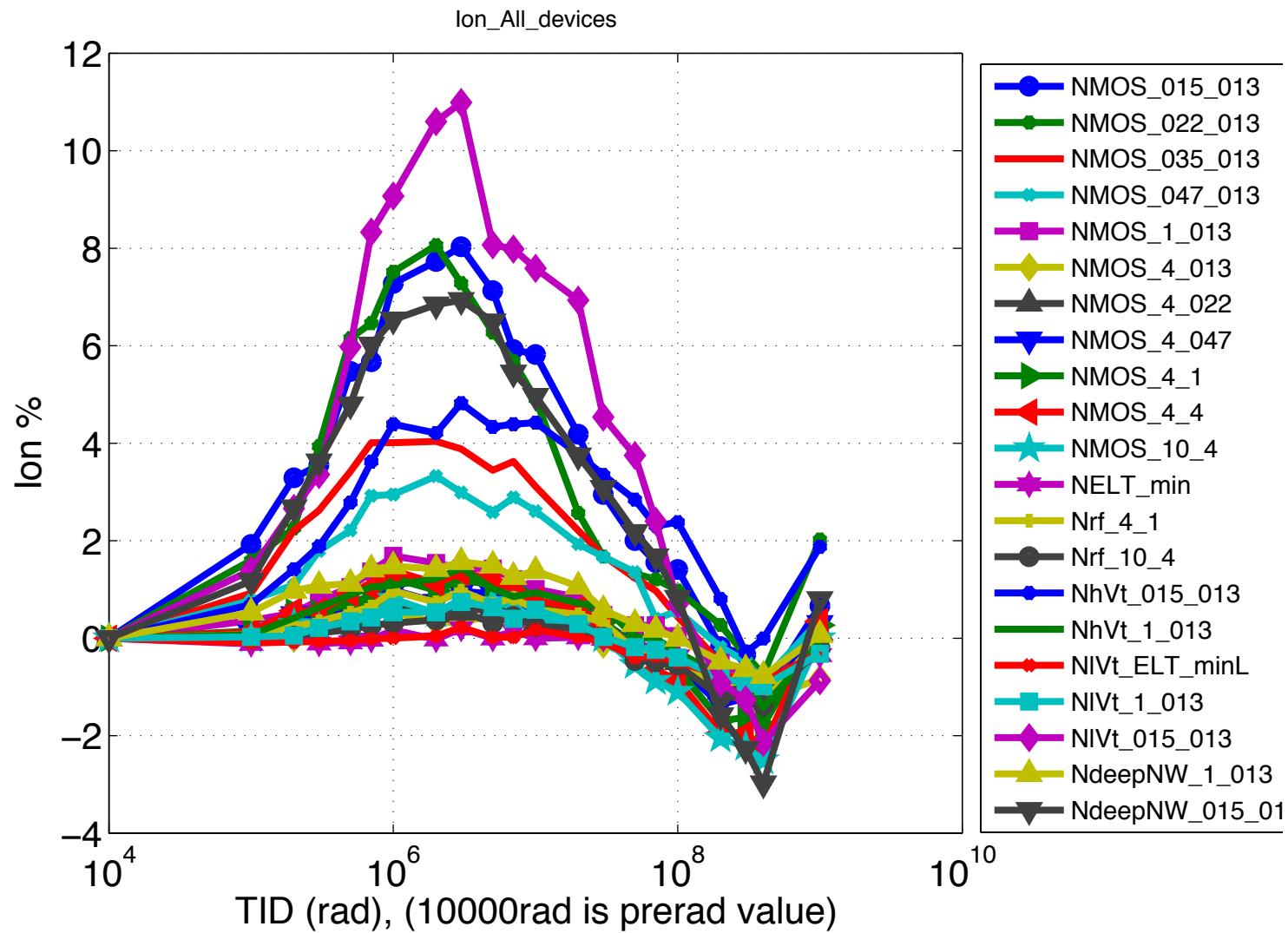


Test Results	Range	Max variation (mV)	Max variation (%)
Temperature	-20C to 30C	1mV	0.3%
	-20C to 100C	5 mV	1.5%
VDD	0.5 to 1.3V	1.5mV	0.5%
TID	up to 400Mrad	3mV	1%



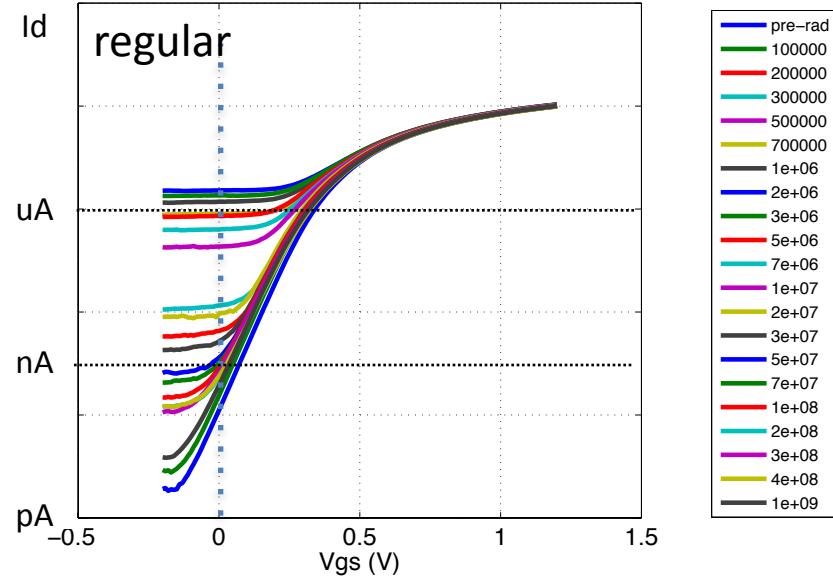
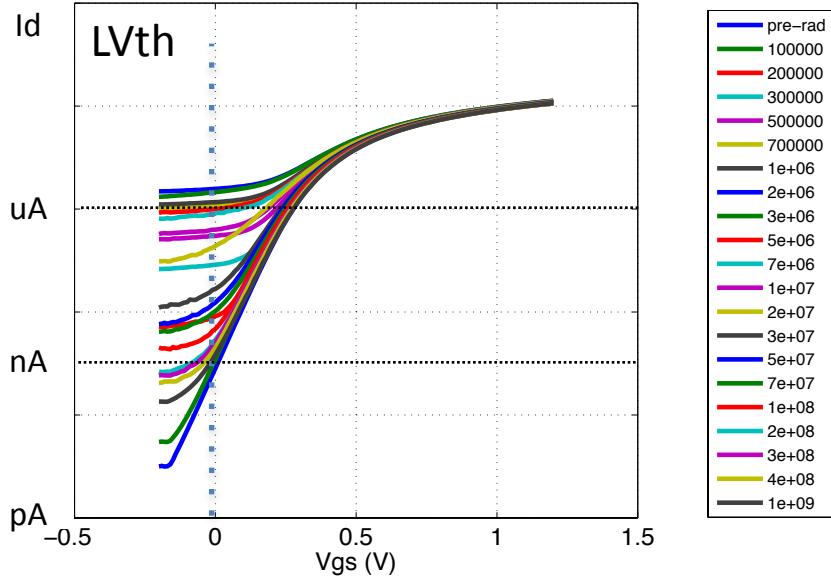
# Backup Slides

# Core NMOS Ion degradation



# NMOS 0.15/0.13 Id Vg – HDR, 25C

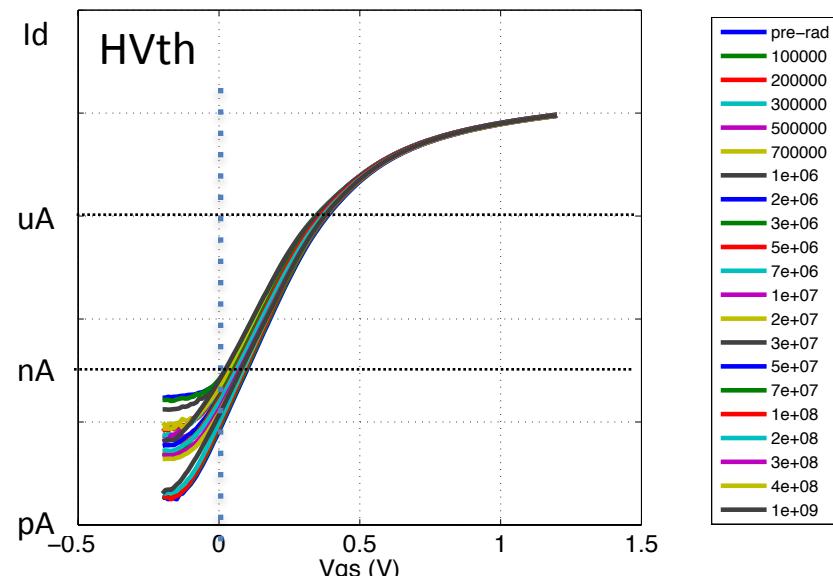
plot from Fab14 12inches



At 25C with high dose rate low Vth and regular transistors suffer of an important increase of the I\_leak (up to 2uA)

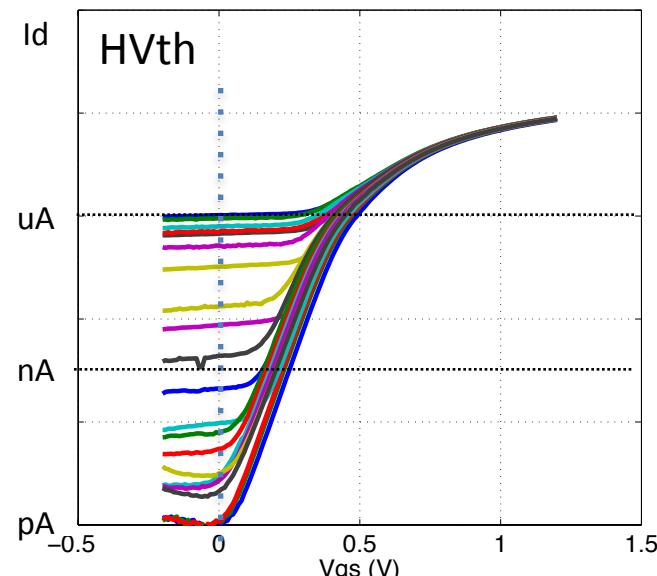
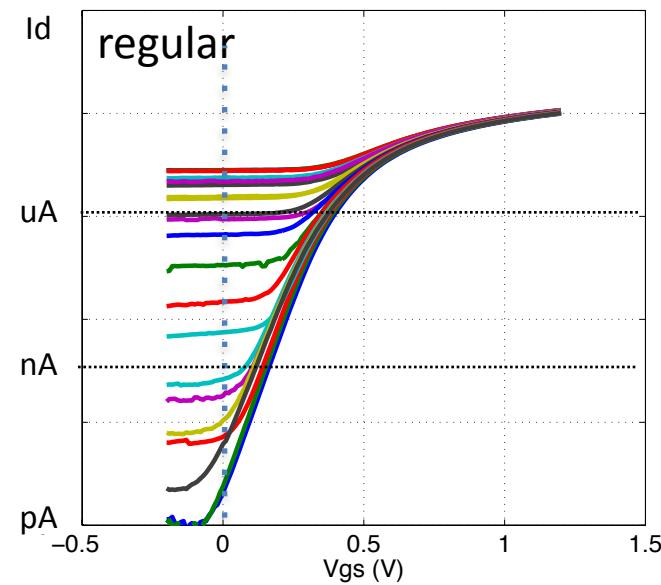
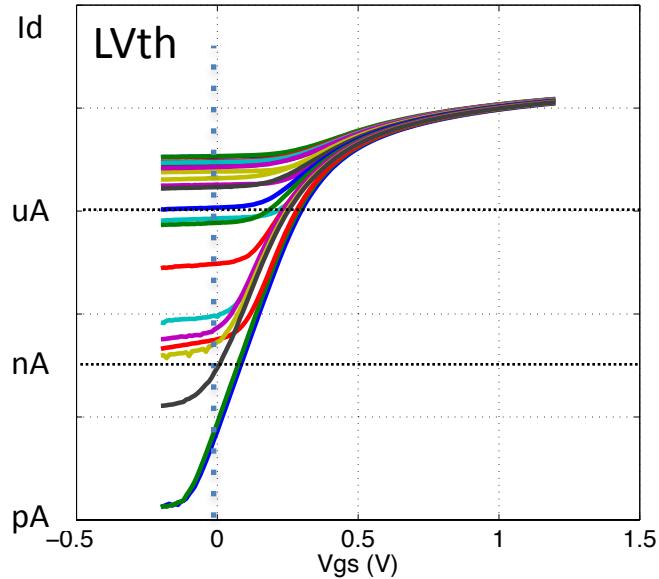
HighVth transistors instead have a negligible increase of the I\_leak.

The extraction of the Vth shift is difficult and meaningless with the large increase of leakage current.

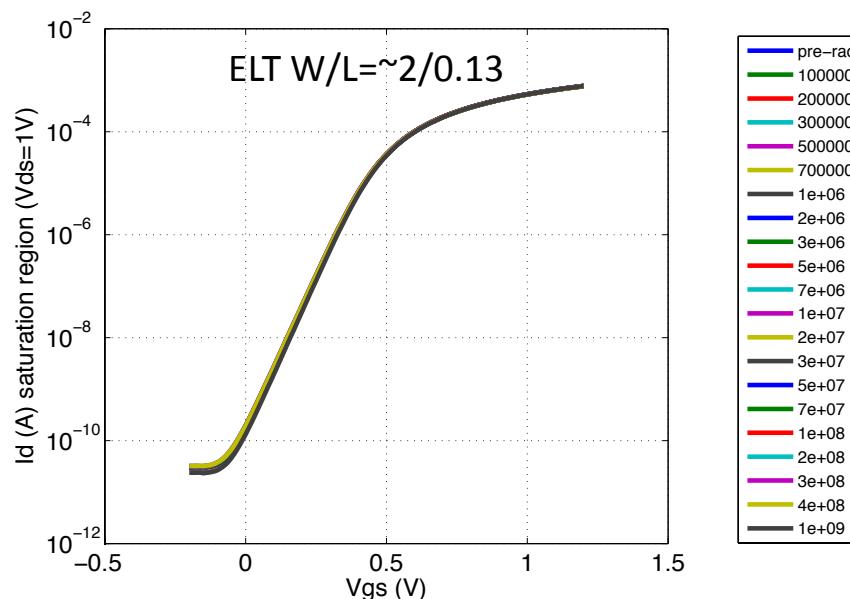
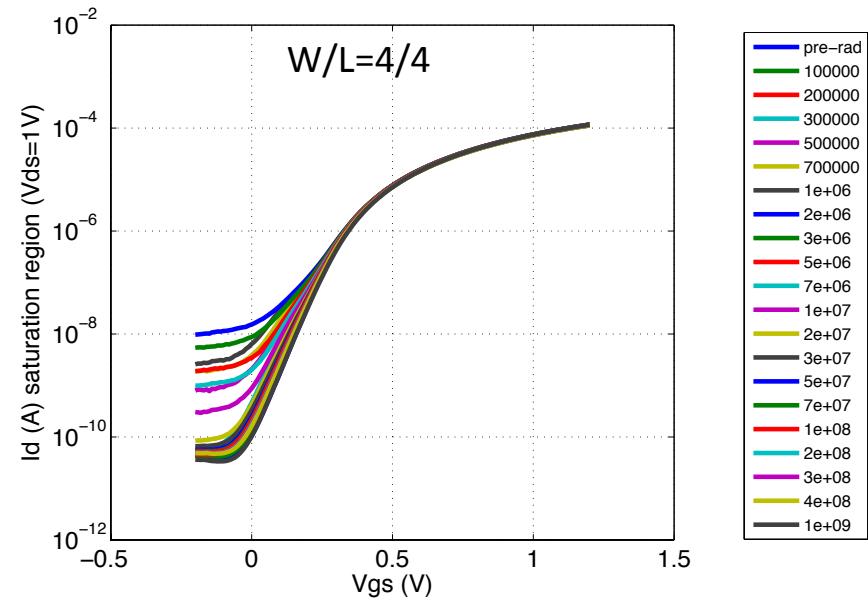
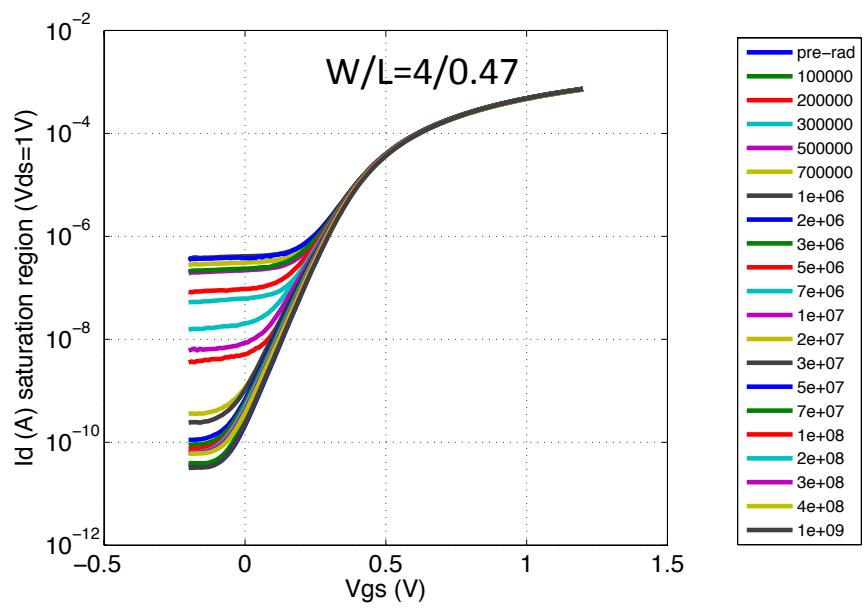


# NMOS 0.15/0.13 Id Vg – HDR,-30C

plot from Fab14 12inches



# IdVg of ELT and big transistors

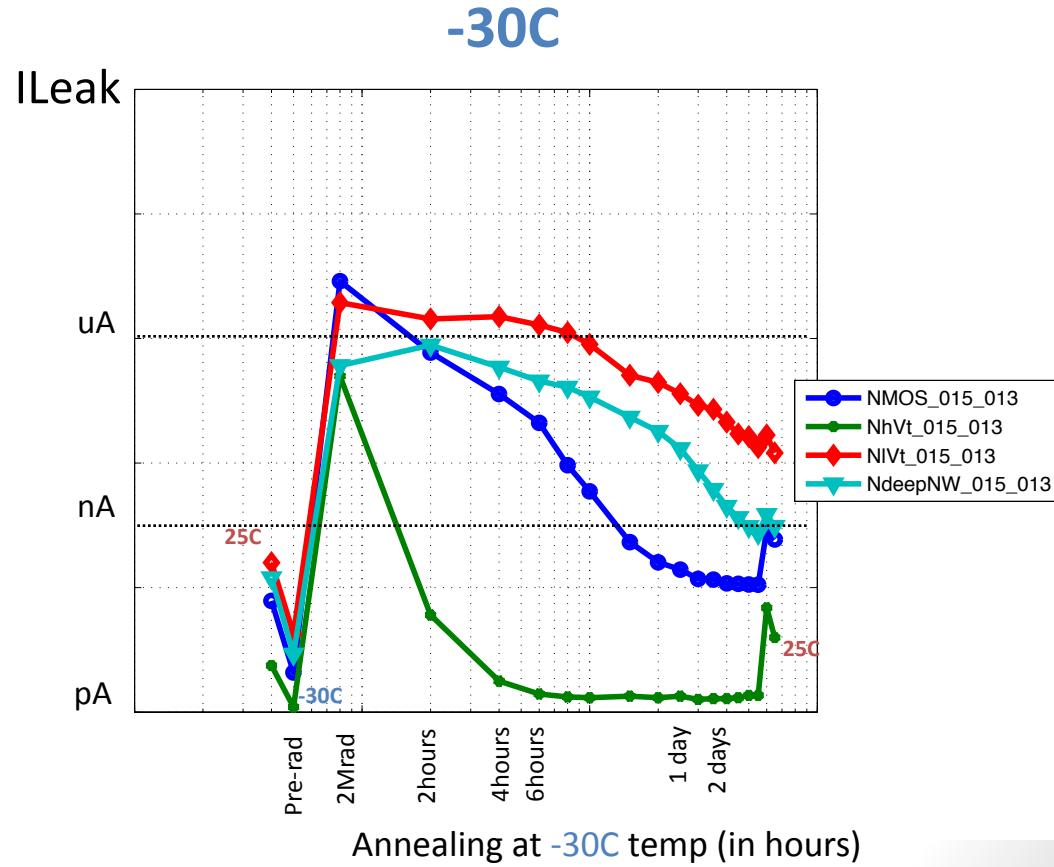
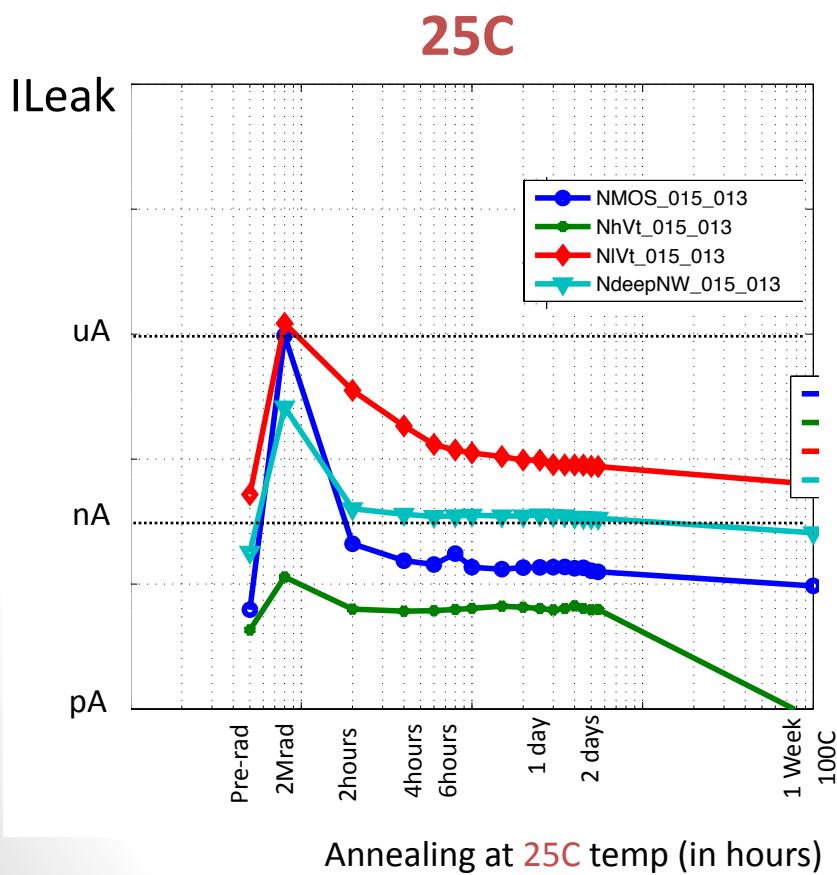


plot from Fab14 12inches

# NMOS Leakage current with annealing

We want to see the impact of annealing at **25C** and **-30C**

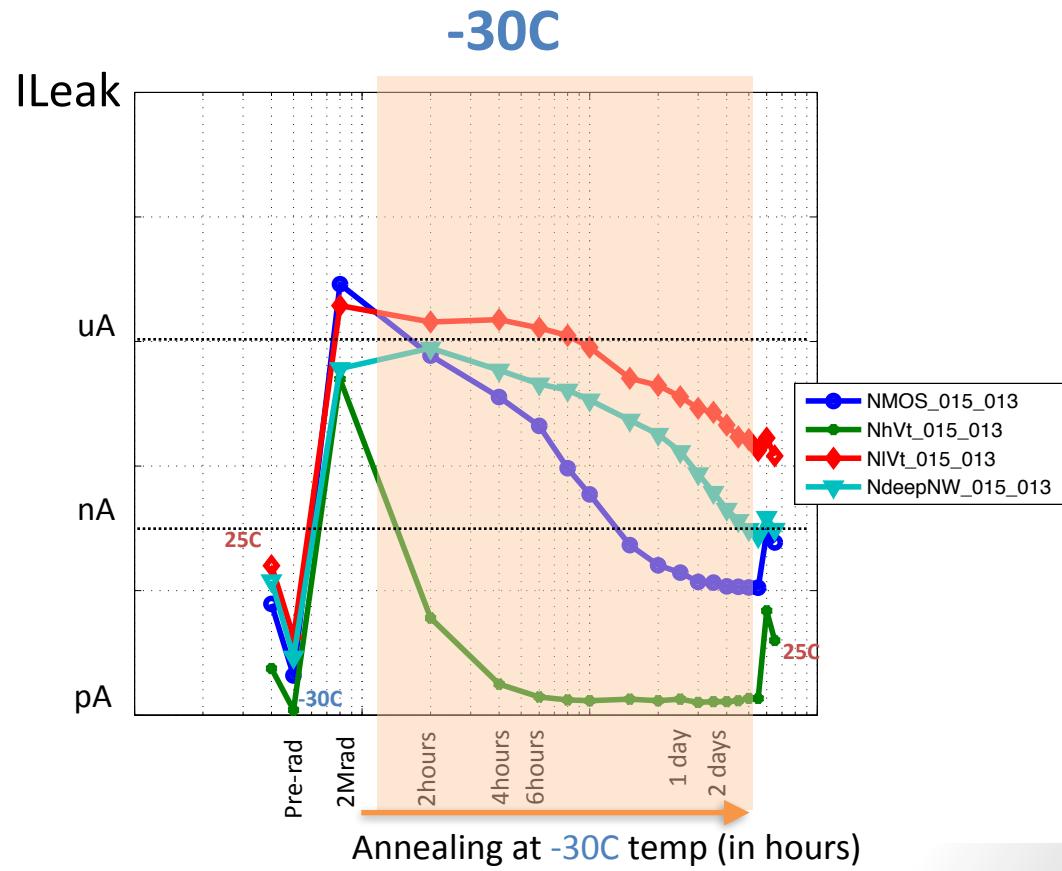
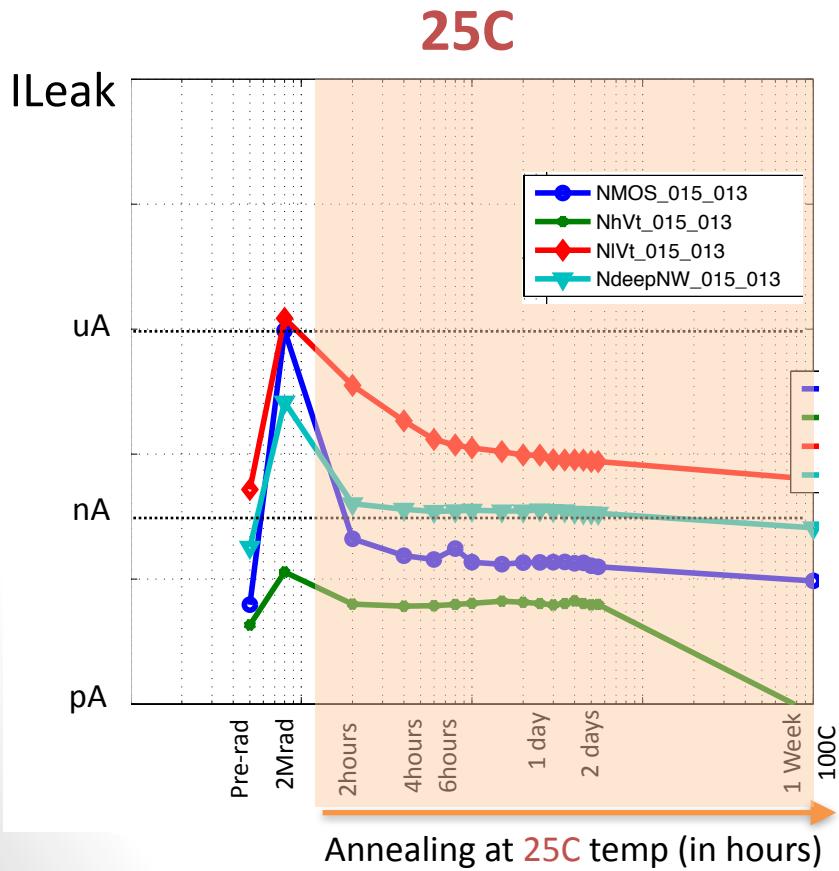
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annealing for 48 hours with 2-5h delay between measurements



# Summary of NMOS core results

All NMOS flavors present a large increase of leakage current with TID (except hVt at **25C**)

<b>NMOS I_Leak 25C/-30C</b>	<b>Pre-rad (A)</b>	<b>Peak HDR (A)</b>	<b>Peak LDR (A)</b>
<i>Low Vth</i>	<b>1n/80p</b>	<b>2u/10u</b>	<b>800n/8u</b>
<i>regular</i>	<b>100p/4p</b>	<b>2u/8u</b>	<b>7n/2u</b>
<i>High Vth</i>	<b>80p/1p</b>	<b>700p/1u</b>	<b>-/15n</b>

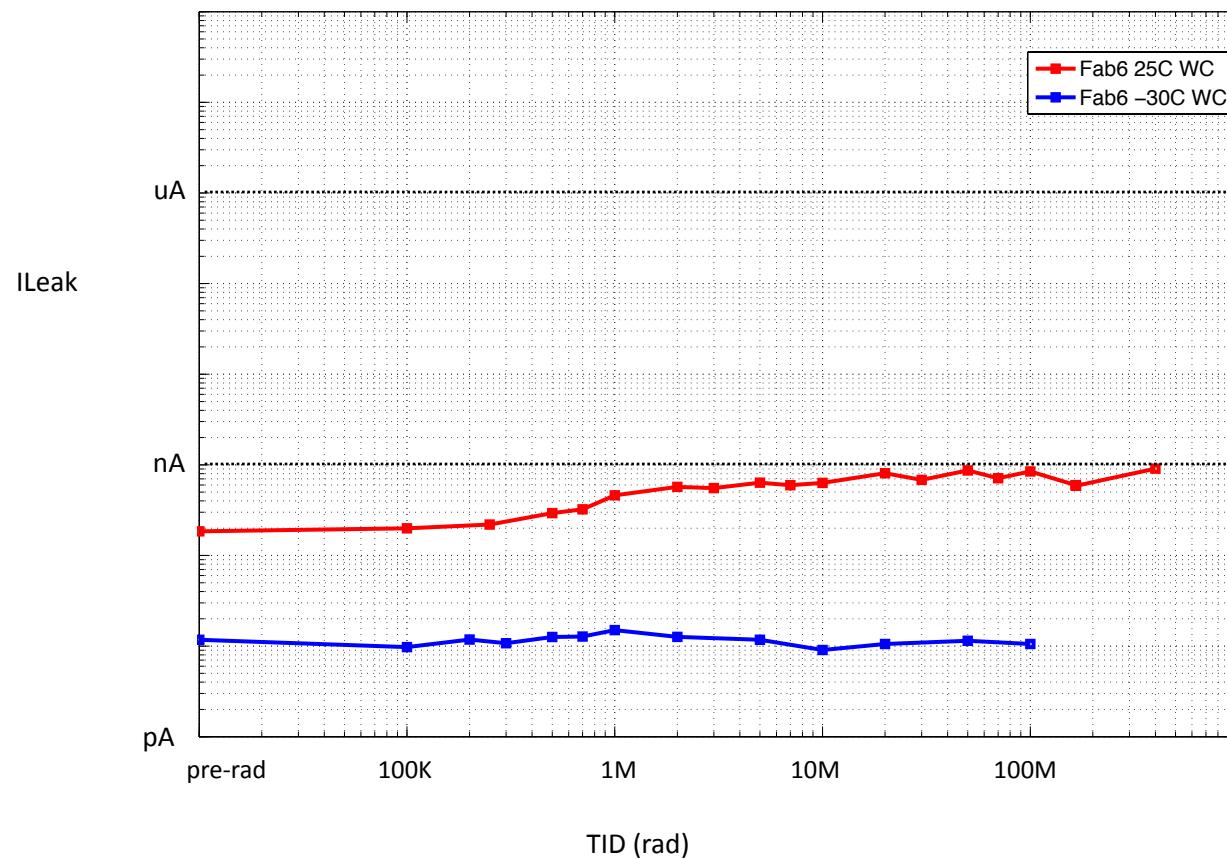
The annealing time is rather fast: hours at **25C**, days at **-30C** (hours for hVt)

There is no degradation of the Ion (-2% at 400Mrad)

It is evident that there will issues for testing ASICs with big digital blocks (large increase of static current)

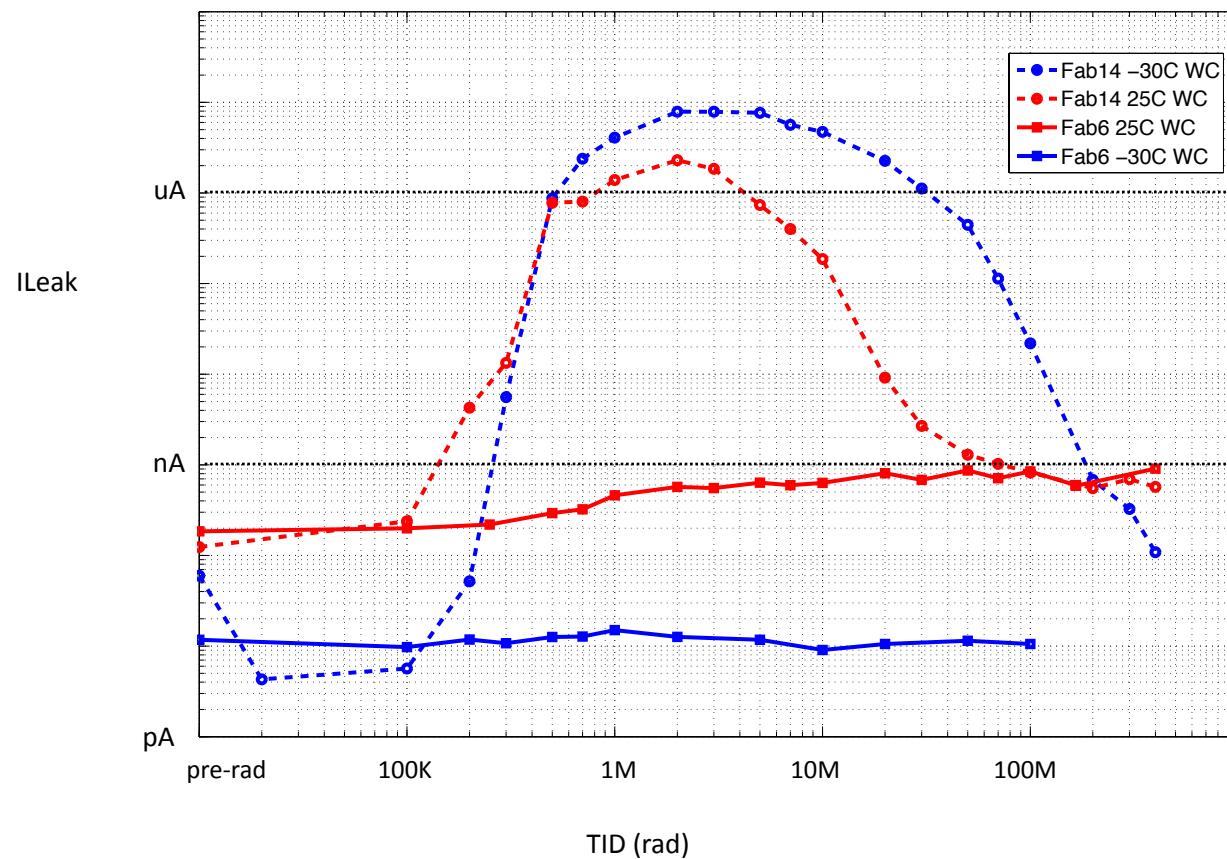
Strong suggestion for using hVt NMOS when possible (no leakage at 25C and at -30C the annealing time is 1-2h)

# Leakage current difference between Fabs



NMOS min size  
0.15/0.13

# Leakage current difference between Fabs

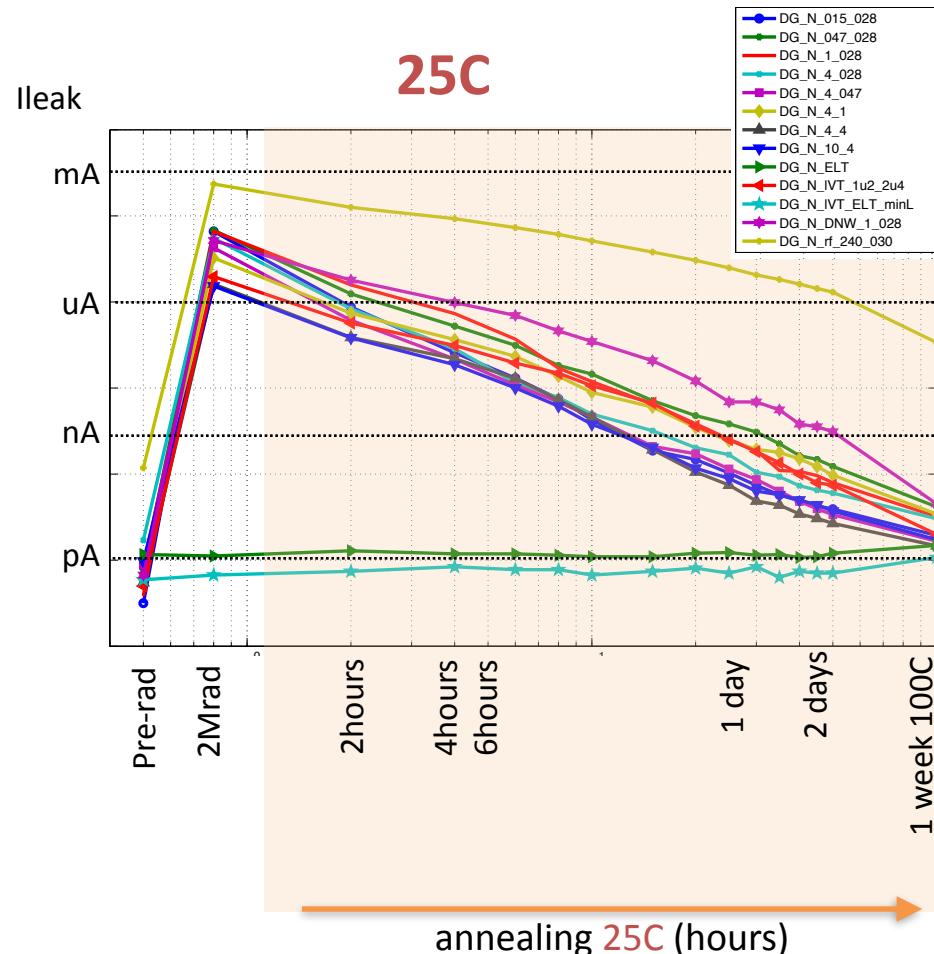


NMOS min size  
0.15/0.13

# I/O NMOS Leakage current with annealing

The aim is the understanding of annealing behavior at **25C** and **-30C**

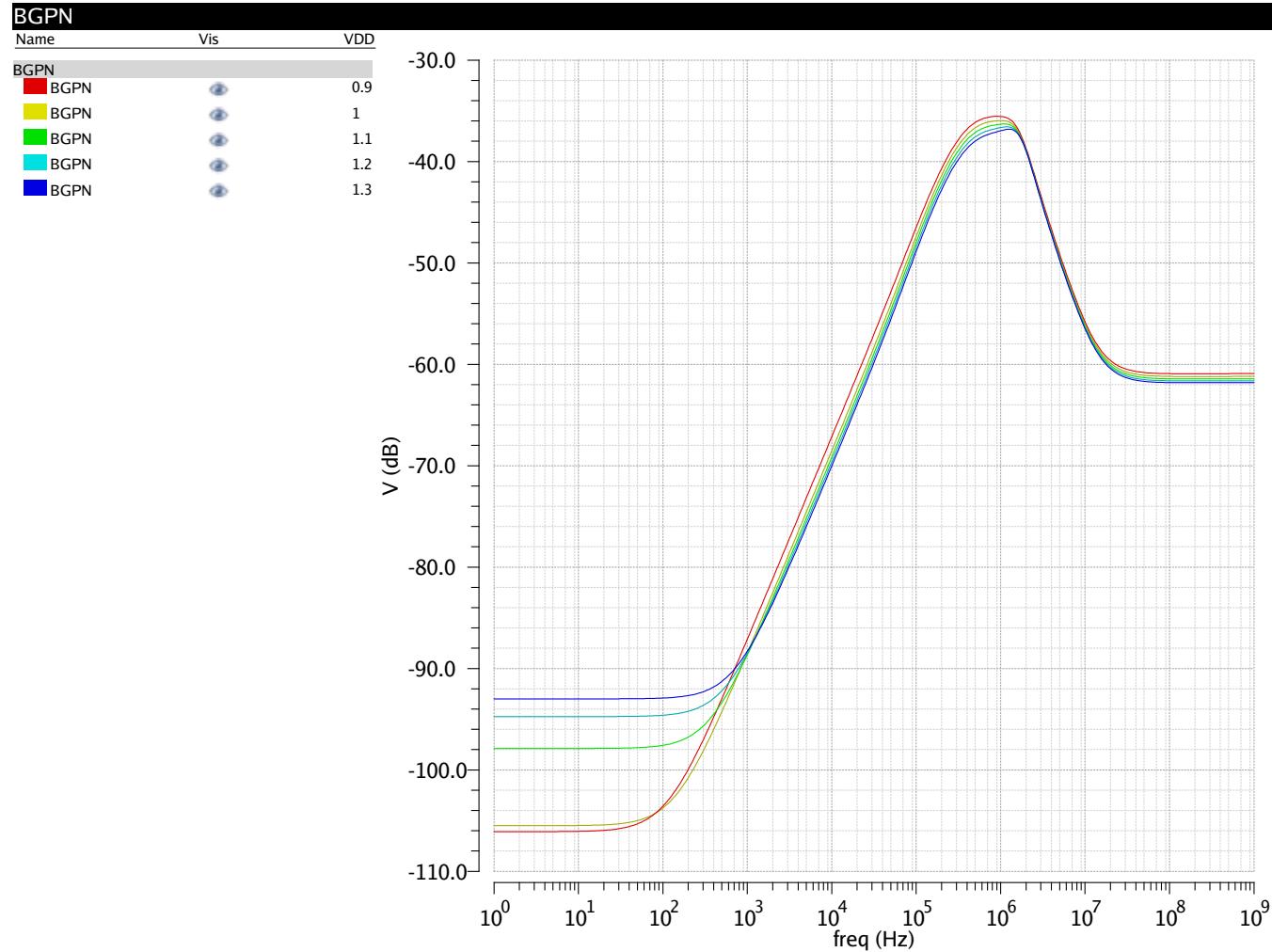
Procedure:      irradiation up to 2 Mrad (highest peak)  
 annealing for several hours with 2-5h delay between measurements



Annealing time:  
 at **25C** is ~days  
 at **-30C** is ~weeks

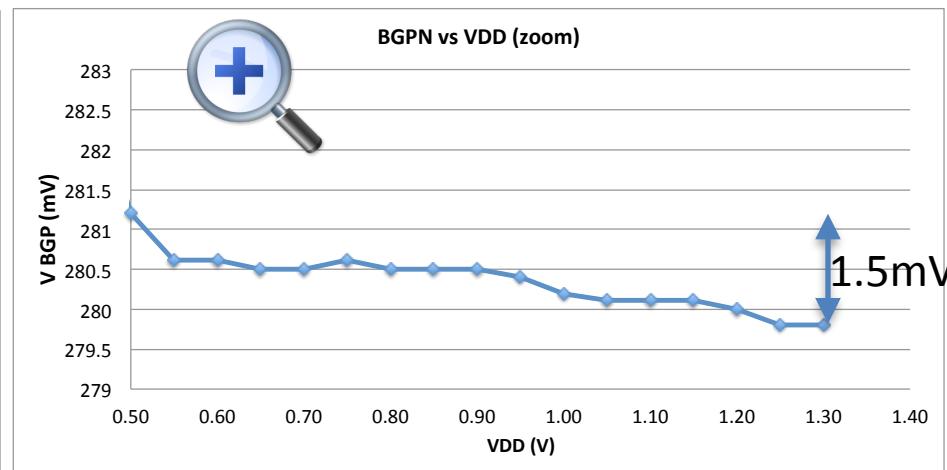
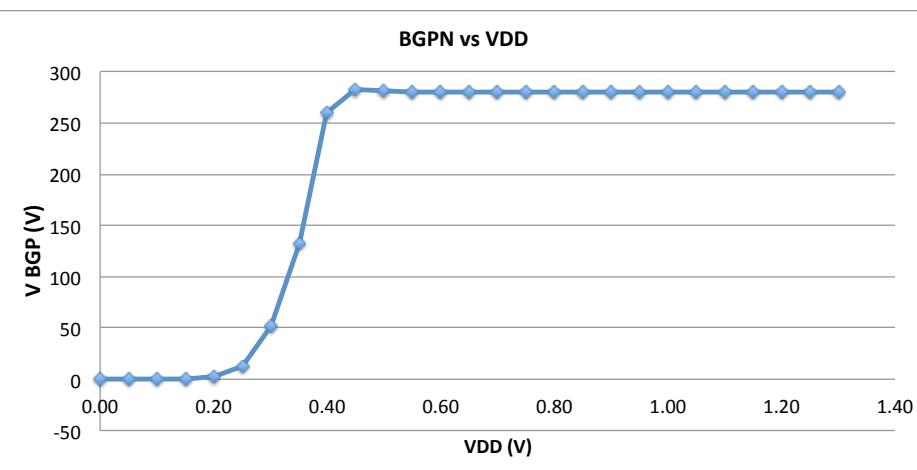
# BANDGAP

# PSRR simulations



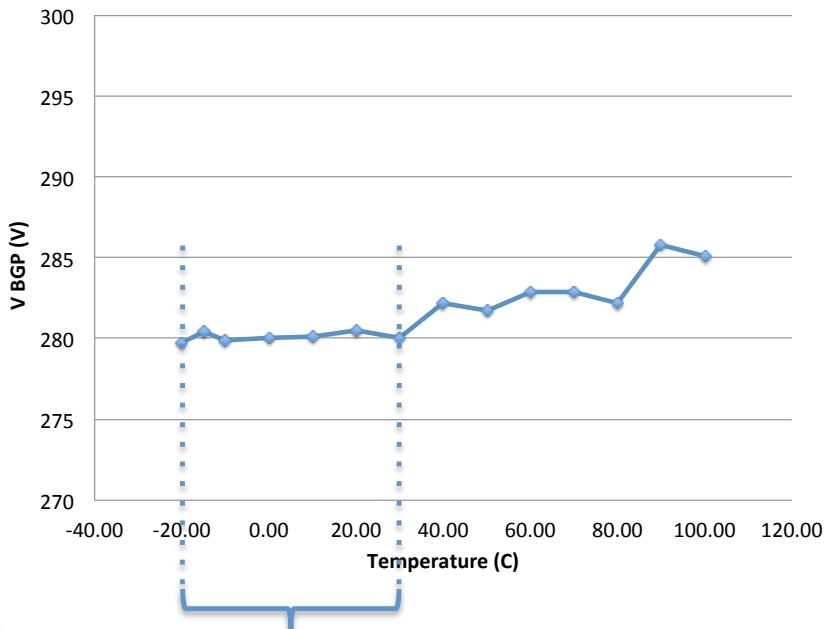
# Bandgap vs VDD (real measures)

The bandgap is operative starting from  $V_{dd}=0.5V$   
the variation of the Bandgap in the range of  $V_{dd}=0.5-1.3V$  is  $1.5mV$



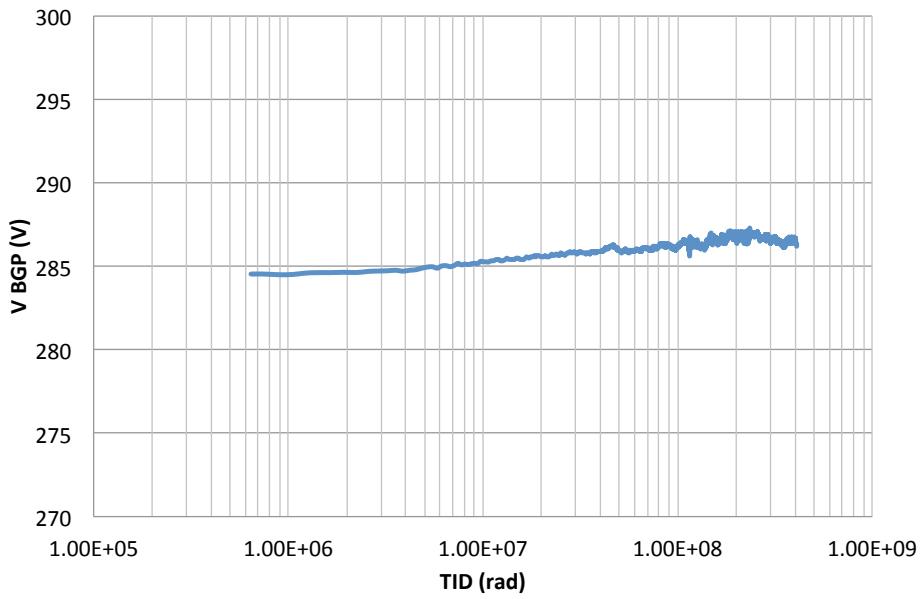
# Bandgap vs T and TID

Bandgap vs Temperature



In the range from -20C to 30C the variation is less than 1mV

Bandgap vs TID



3 mV variation over 400Mrad